

Fabrication of nanostructures and nanoscale devices.

Part 6.

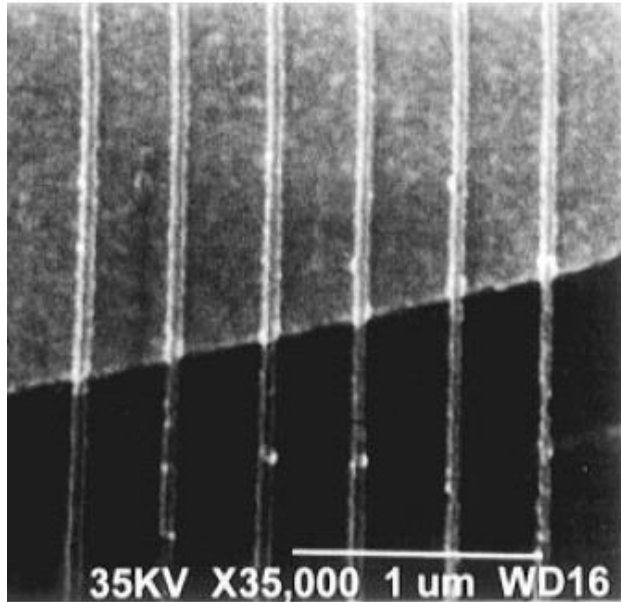
Galina A. Tsirlina

galina.tsirlina@nanocenter.si

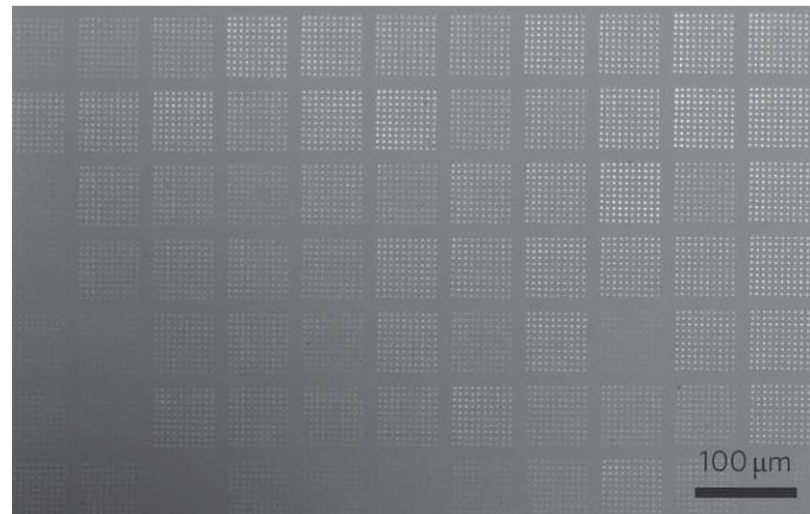
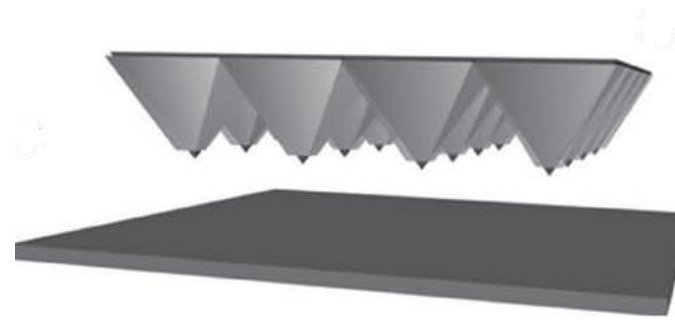
galina.tsirlina@protonmail.com

See the lectures at <https://www.nanocenter.si/qt-future/education-2/>

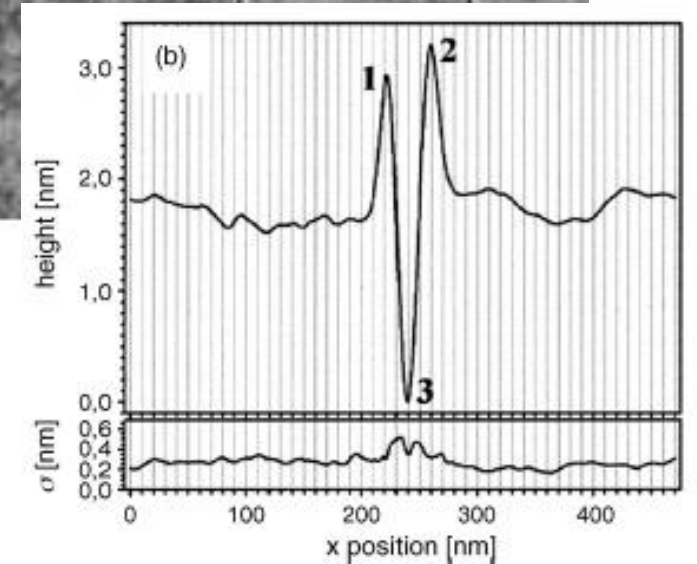
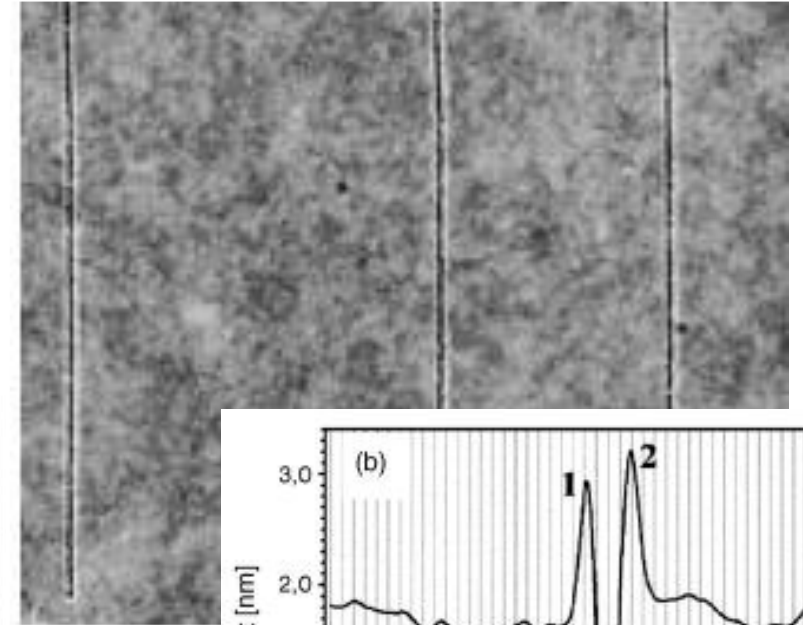
ca. 40 nm resolution



Chem. Rev. 97 (1997) 1195



Macromol. Rapid Commun.
33 (2012) 359



**Mechanical + thermal
effect on the polymers**

Mater. Sci. Eng. R54 (2006) 1

Principle technological schemes

Part 5 Optical and Electronic Lithography

Polymer and inorganic resists (composition, solubility, microstructure)

Spin-coating, adhesion, roughness

Light and beam interactions with positive and negative resists; amplification

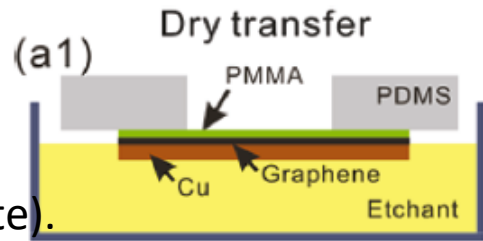
Post-exposure procedures (developers, thermal effects, wetting)

Maskless lithography

Part 6 Assembling of low-dimensional objects

- Dry transfer methods
- Wet transfer methods
- Junctions, contacts
- nm-size gaps

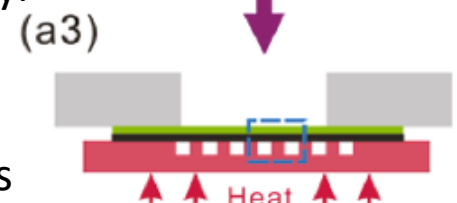
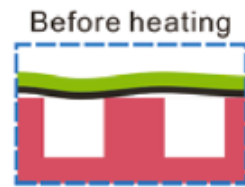
General schemes of the transfer of a single flake (example for CVD graphene grown on Cu)



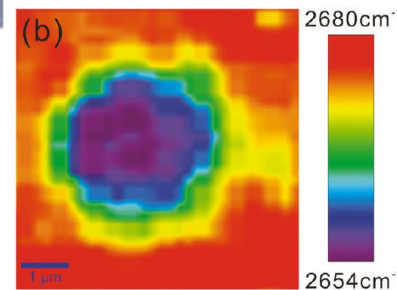
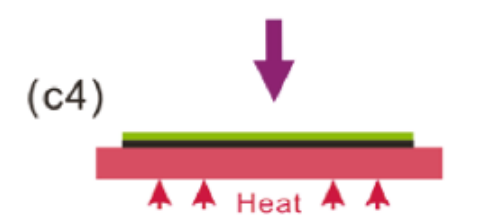
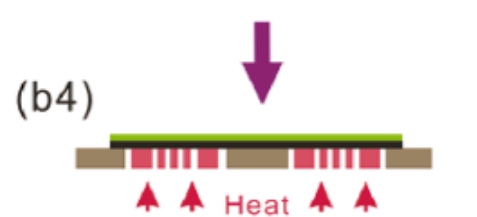
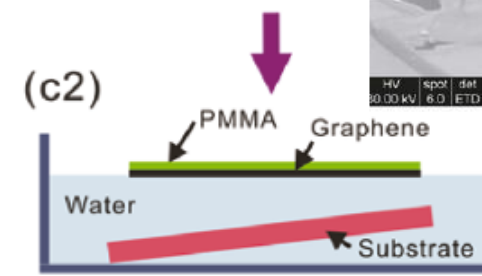
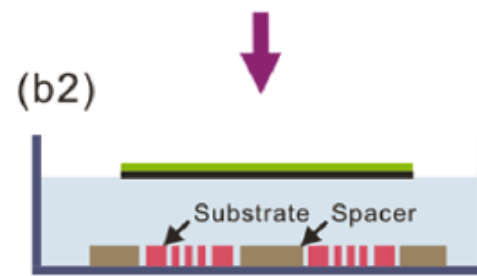
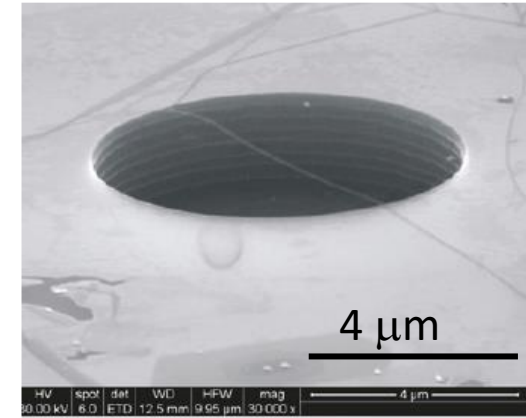
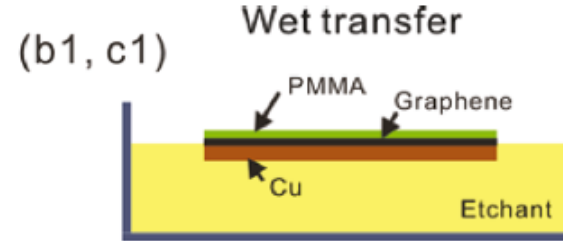
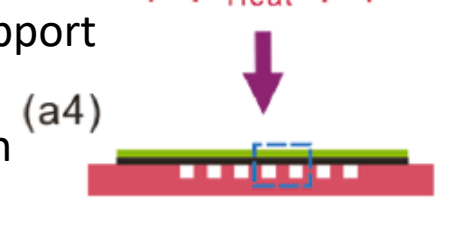
Etchant is oxidizer (e.g. peroxodisulfate).



Polymers are deleted by heating (PDMS is polydimethylsiloxane; PMMA is polymethyl methacrylate).

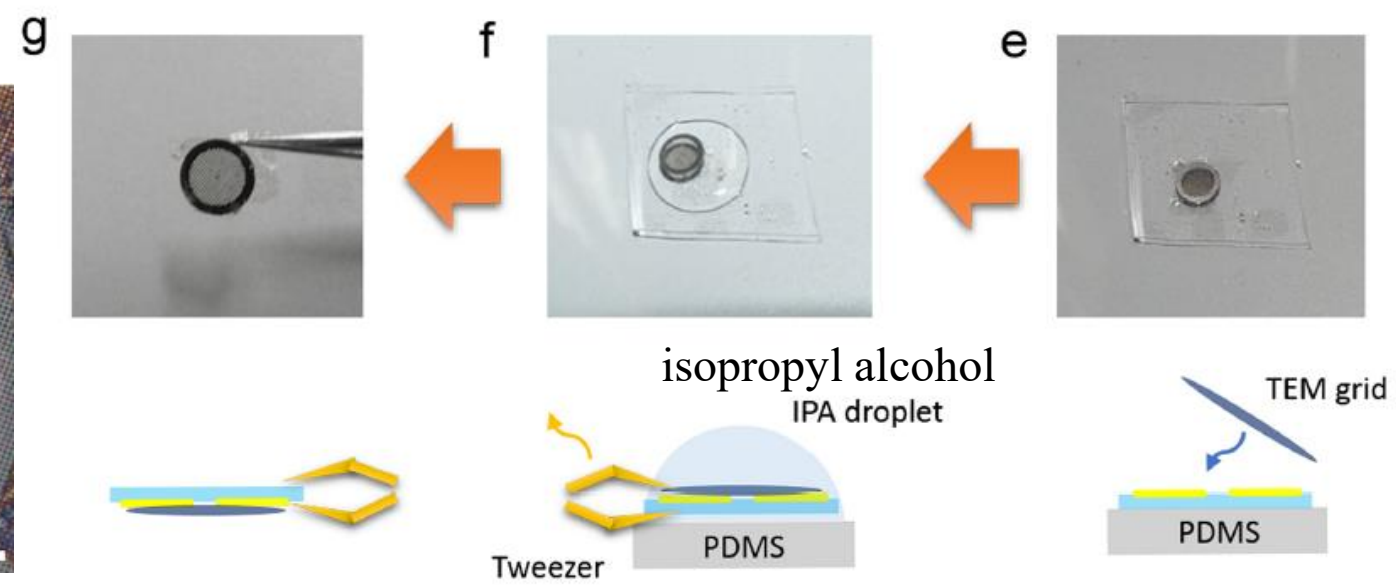
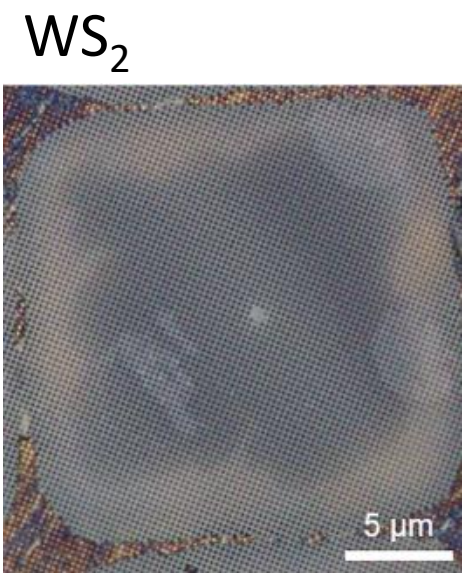
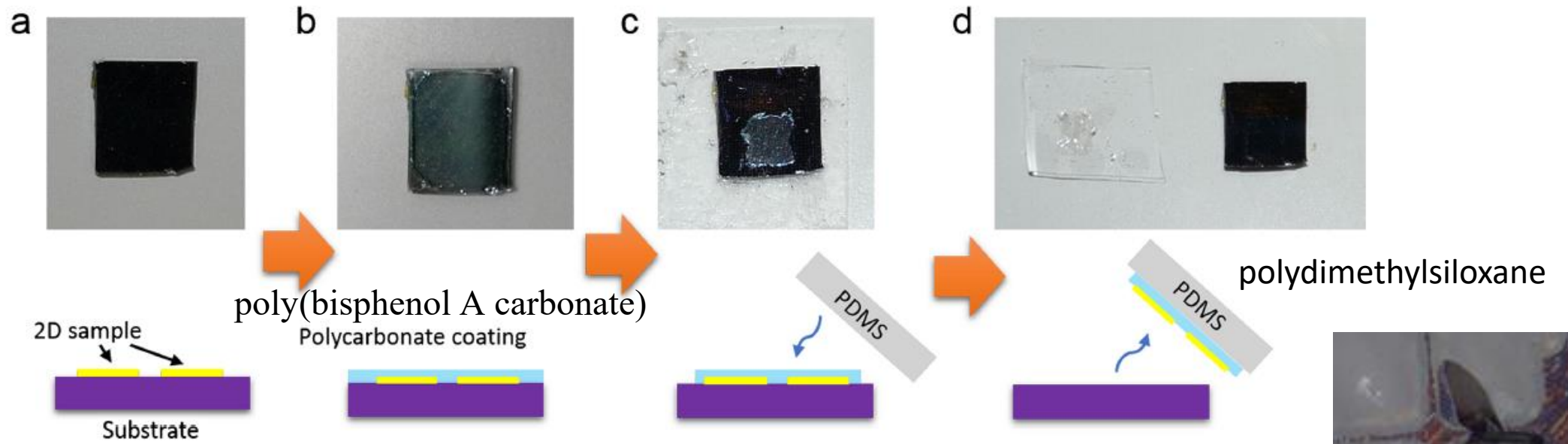


Perforated supports
- decrease flake-support interaction;
- allow transmission microscopy;
- are helpful to delete traces of liquid

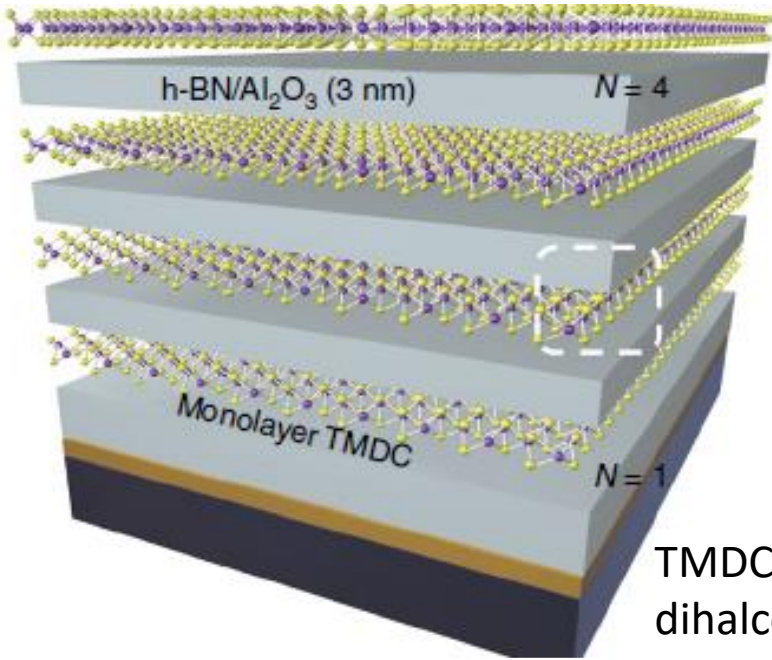


Strain near edges of holes (Raman mapping)

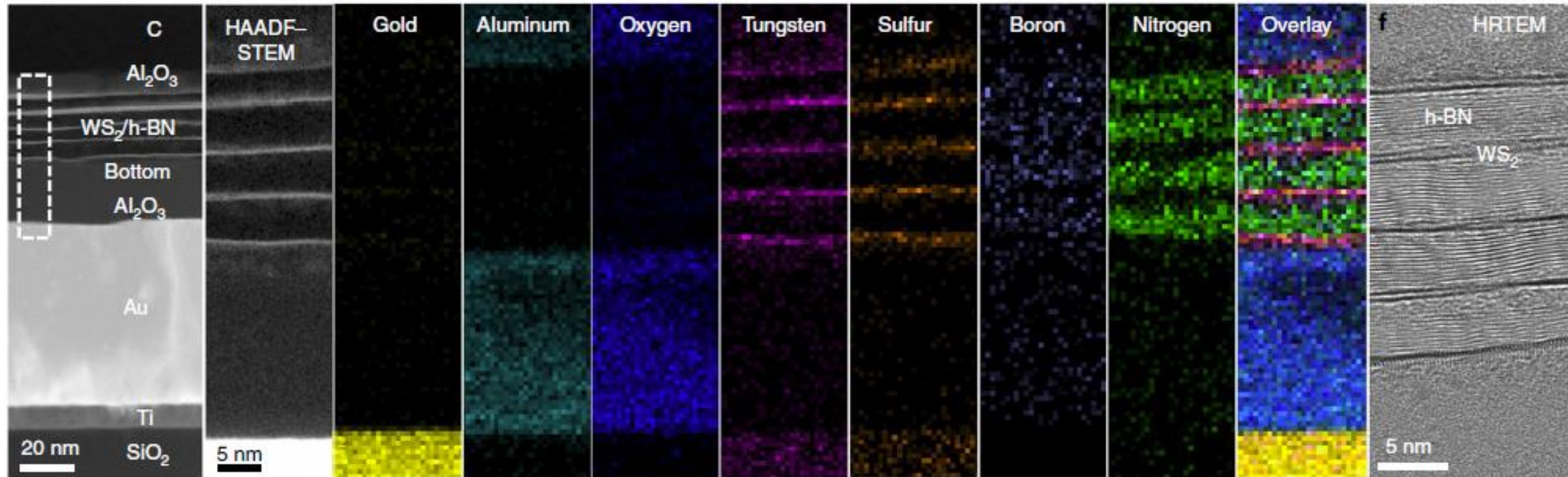
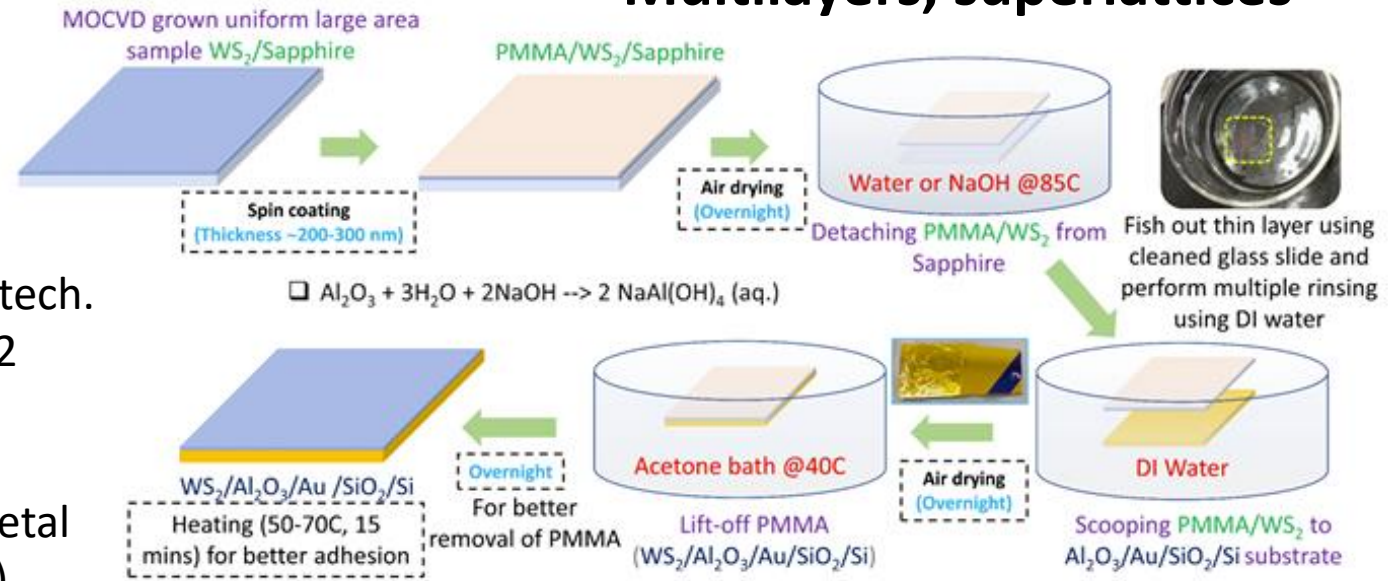
Transfer of a single flake avoiding etching (example of transfer to TEM grid)



Multilayers, superlattices



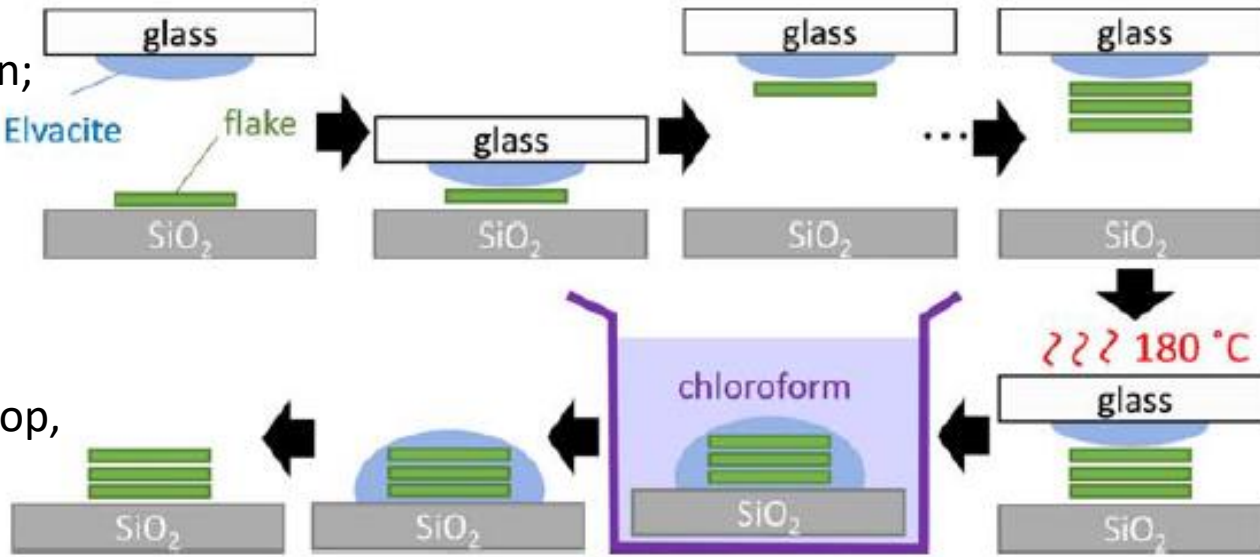
Nature Nanotech.
17 (2022) 182



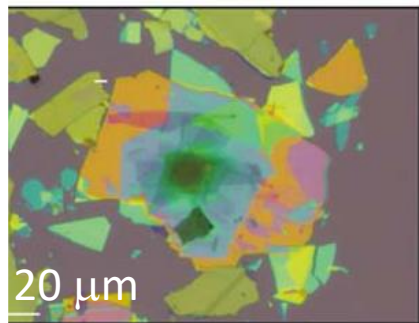
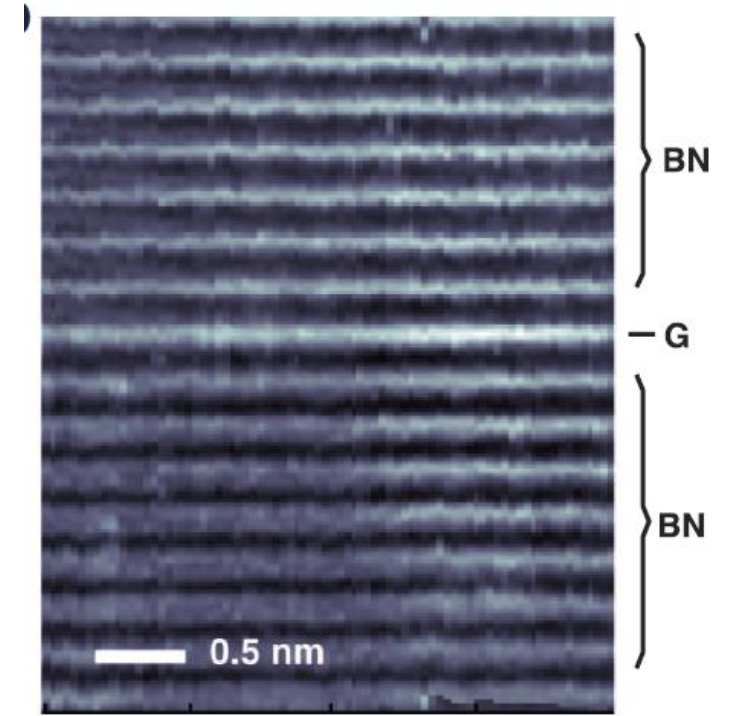
“Pick-up” approach to stacking

Elvacite is acrylic resin; propylene carbonate based polymers can be used as well.

Flake picked up first will finally be at the top, so the structure is not contaminated by polymer stamp



Jap. J. Appl. Phys. 59 (2020) 010101

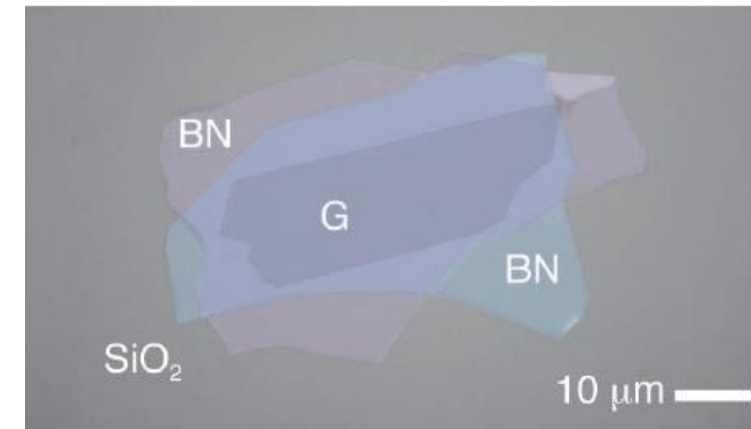


Jap. J. Appl. Phys. 59 (2020) 010101

Dozens of flakes can be stacked, but the size of each flake is occasional.

Optical microscopy is required to combine the central parts of all flakes.

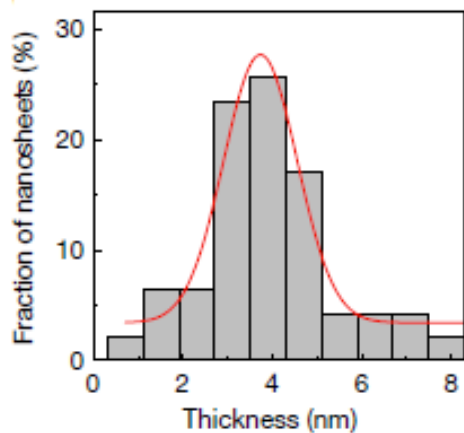
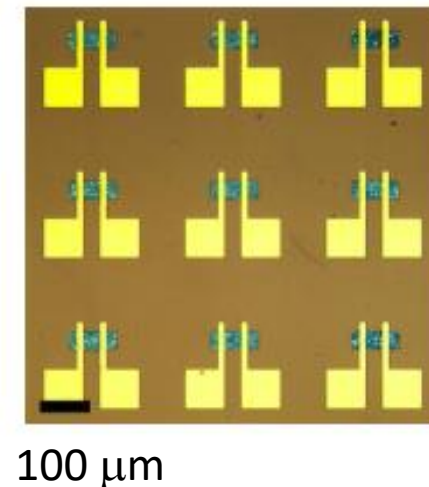
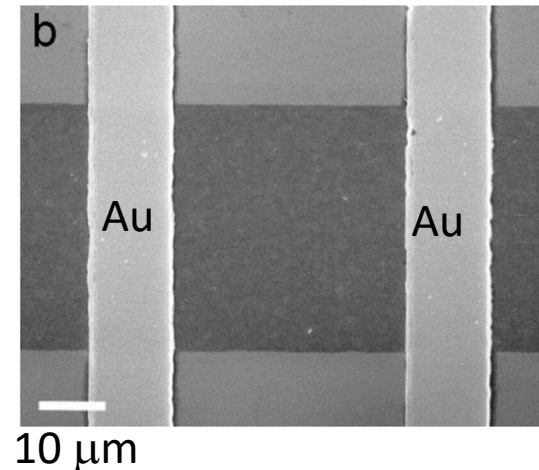
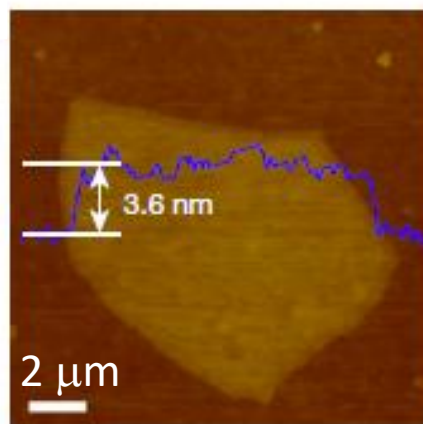
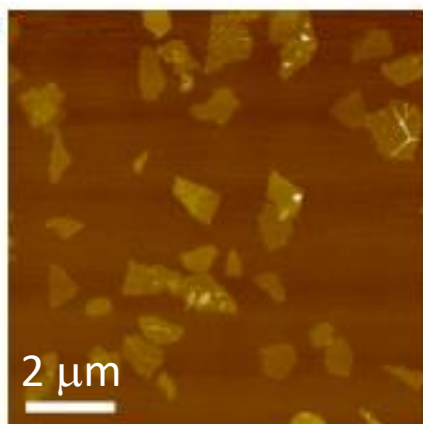
Automatic tools are already developed, but all **single-flake technologies** still work mostly for laboratory prototype devices.



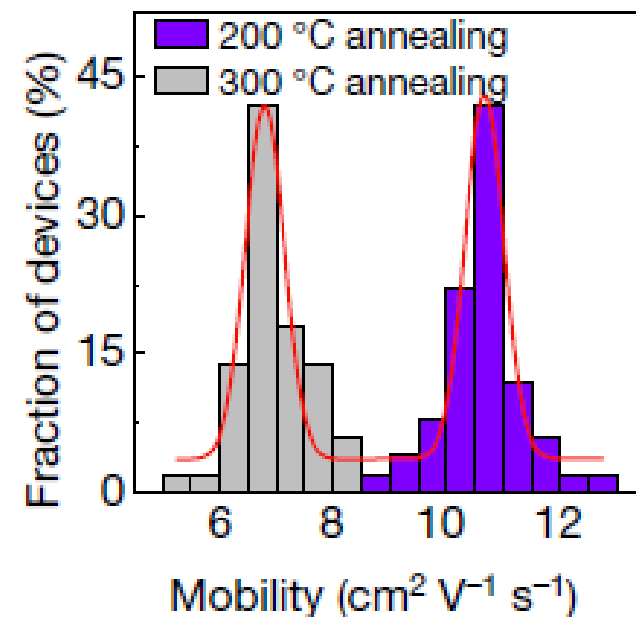
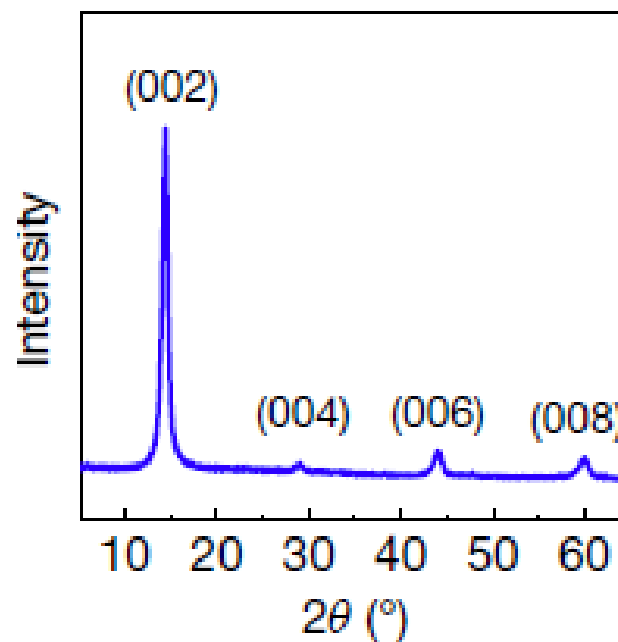
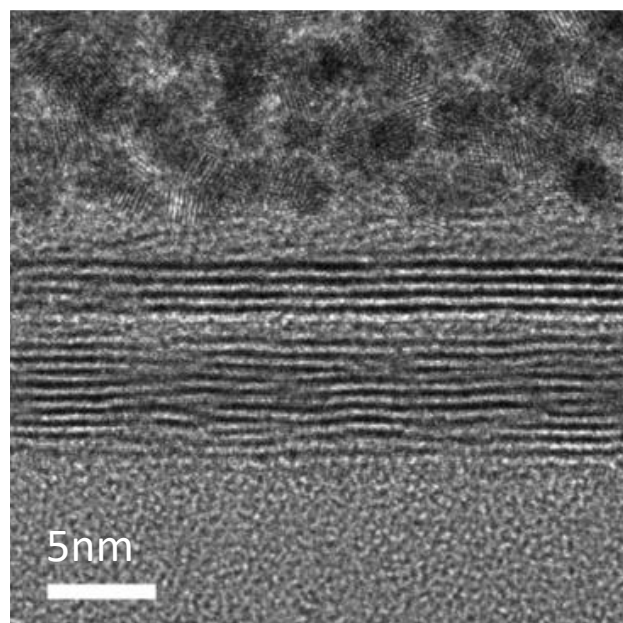
Science 342 (2013) 614-617

Ink-based assembling of 2D flakes (several atomic layers): simple, suitable for any support

Suspension spin-coating, then lithography

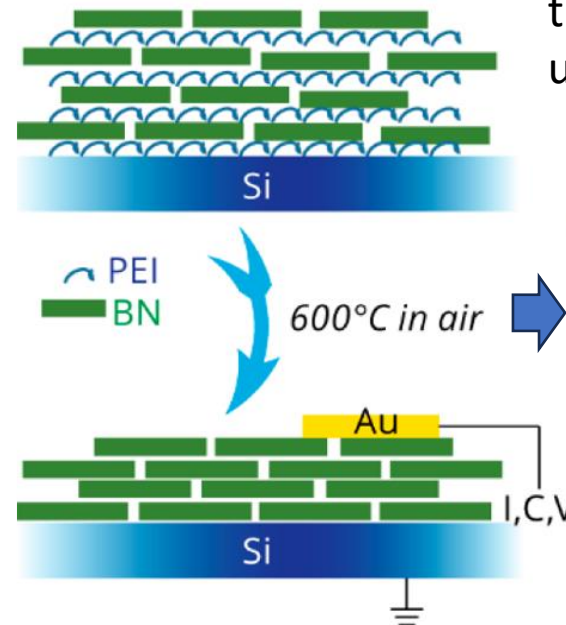
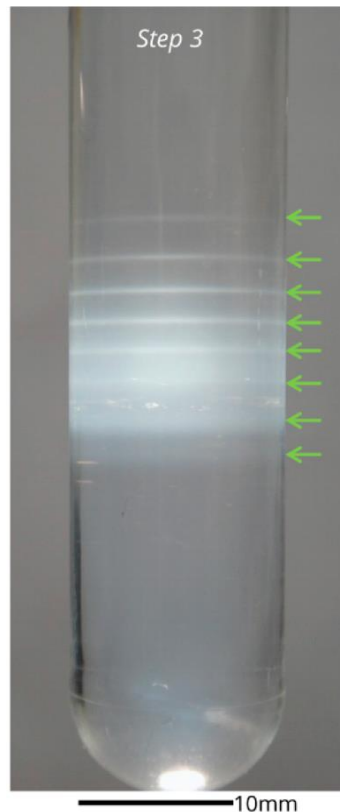
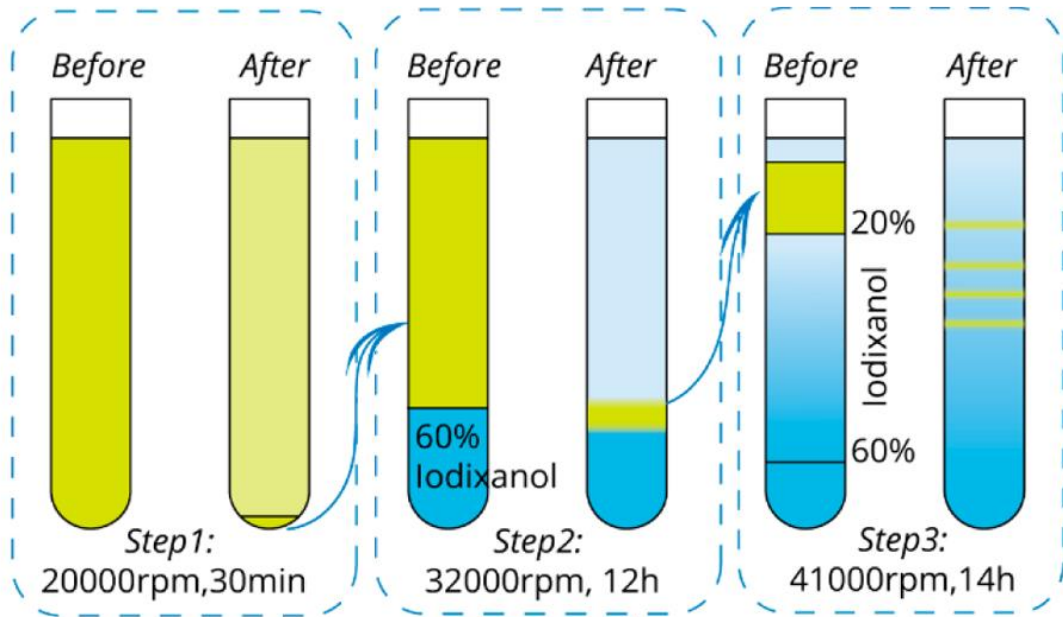


(0.61 nm/layer)

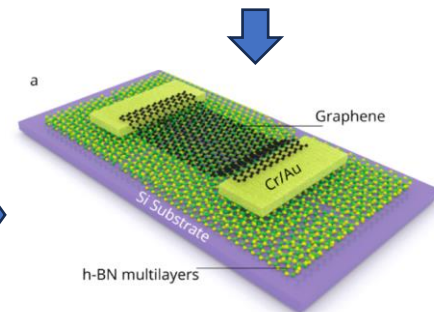


Ink-based assembling of 2D flakes: size/thickness sorting

Centrifugation + extraction, **hexagonal BN:**

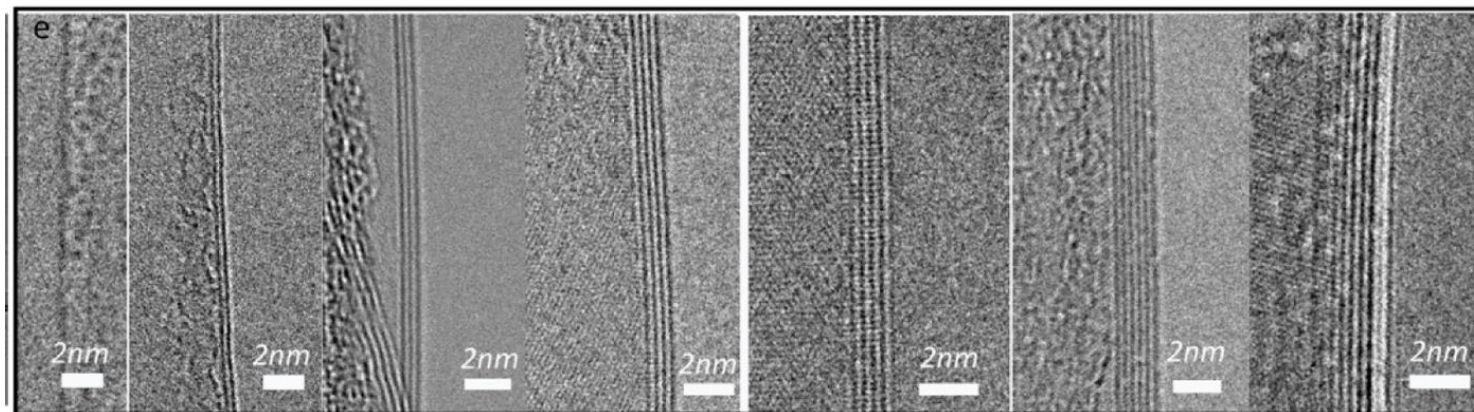
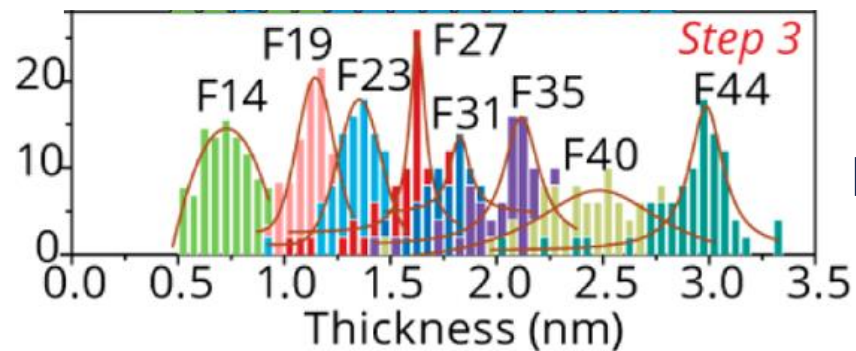


CVD Graphene is transferred from Cu foil using polymer resist

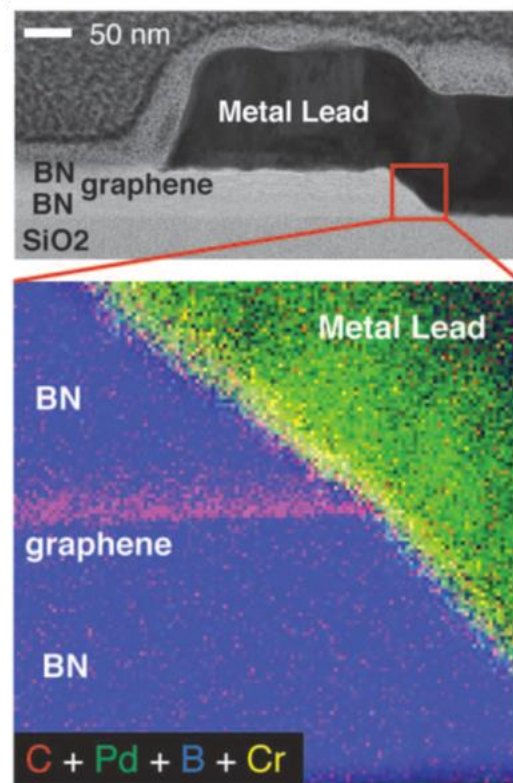
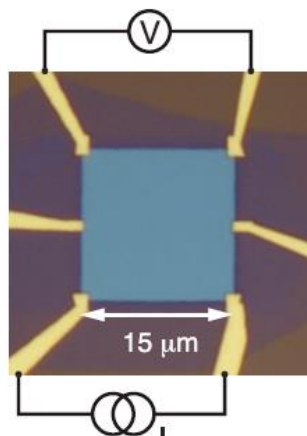
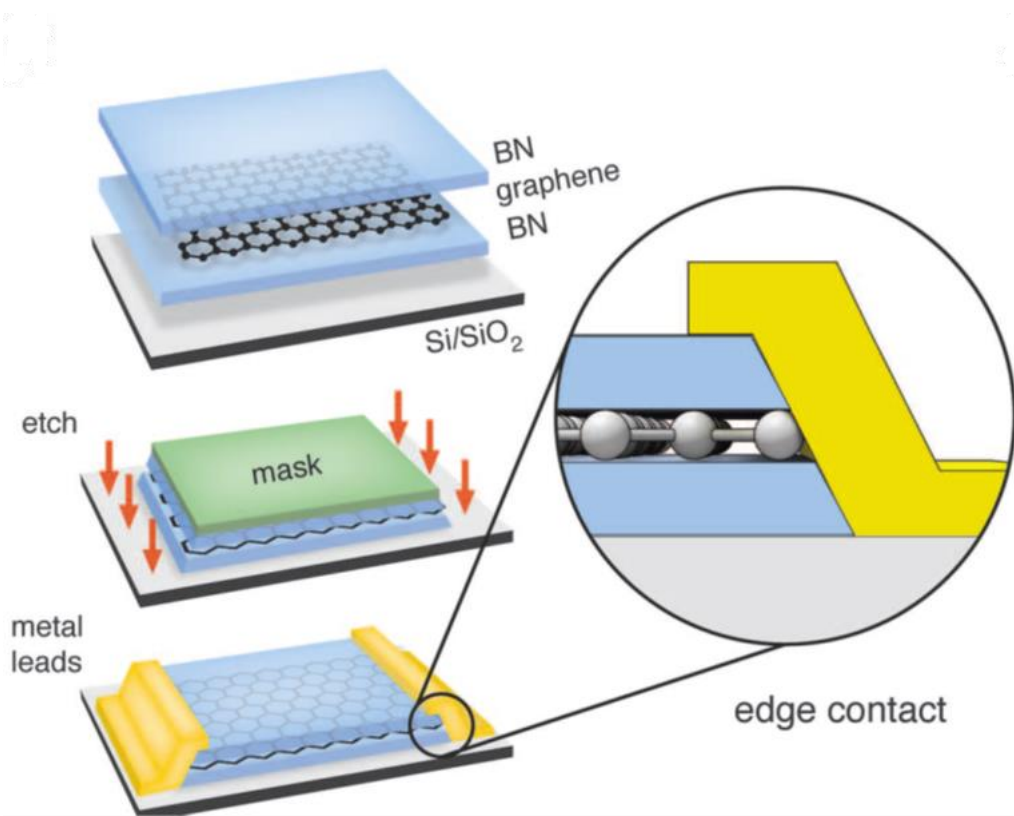


PEI is polyethyleneimine (deleted after heating)

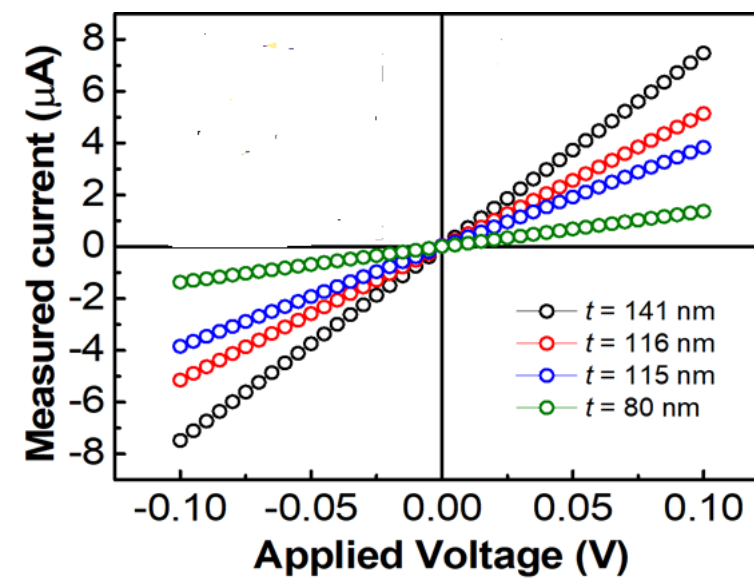
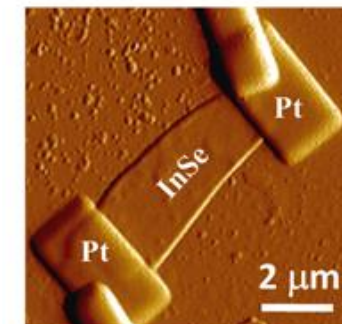
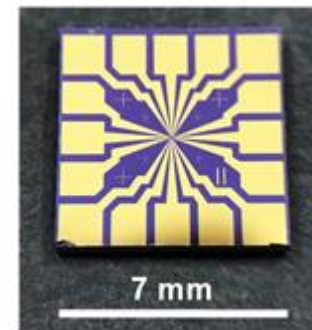
1....7 layers



Edge-contacts to 2D structures



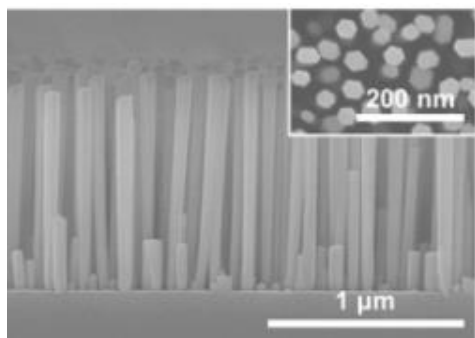
Contacts formed using focused ion beam (FIB)



Structures containing the fragments of various dimensions: 2D and 1D

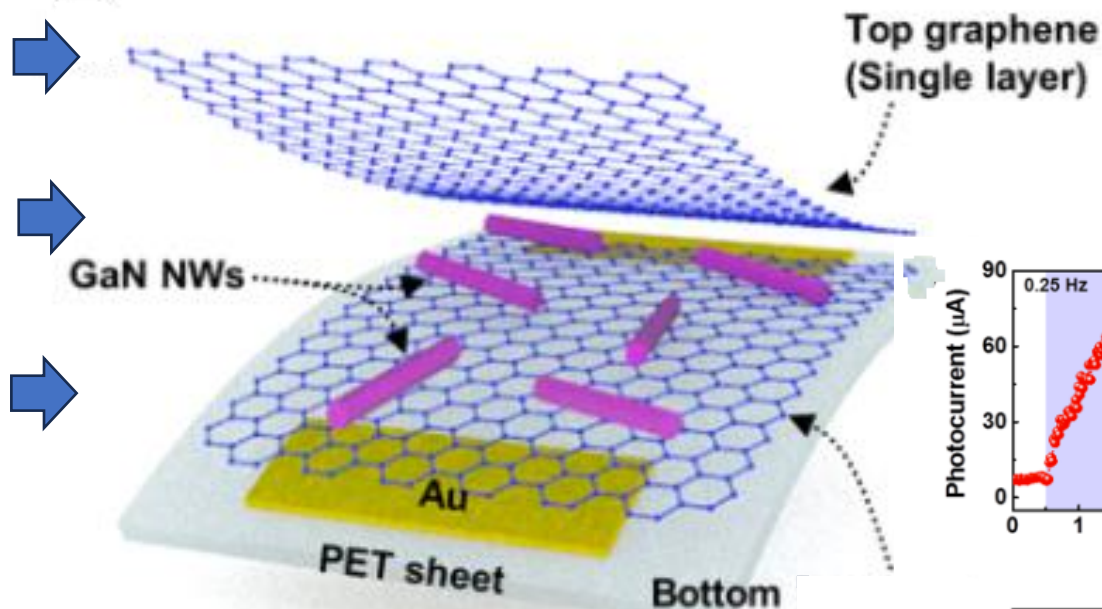
Au sputtering on flexible support (PET = polyethylene terephthalat), $1 \times 0.5 \text{ mm}^2 \times 27 \text{ nm}$; $60 \text{ }\mu\text{m}$ between two Au contacts.

Graphene, up to 3 layers, wet transfer.

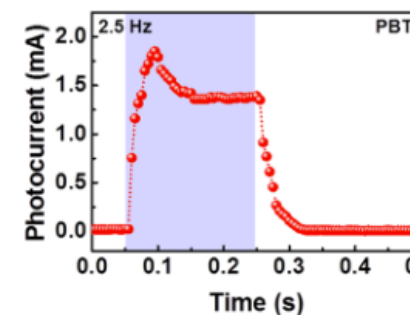
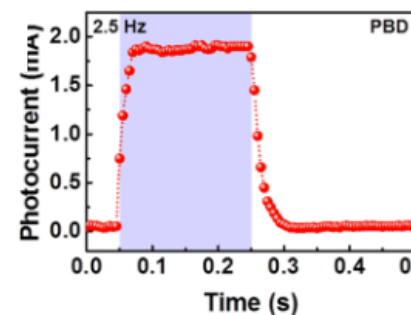
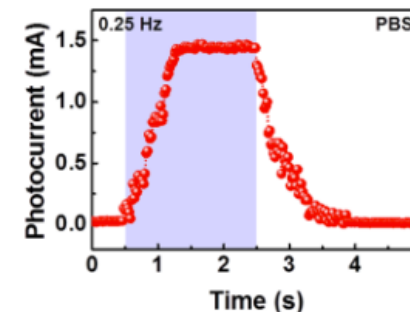
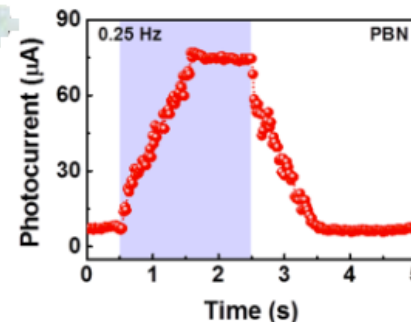
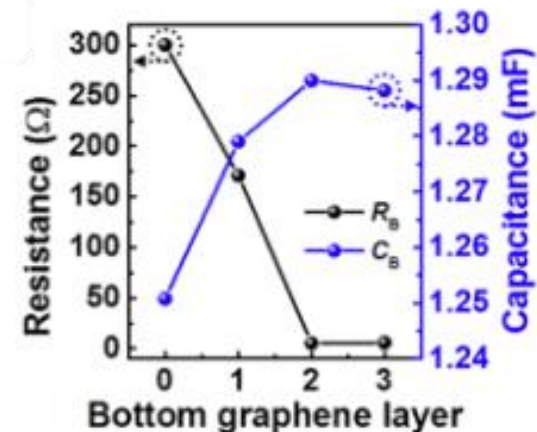


GaN wires grown on Si:
 - **suspended**,
 - randomly deposited.

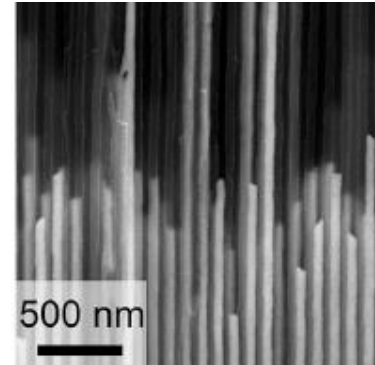
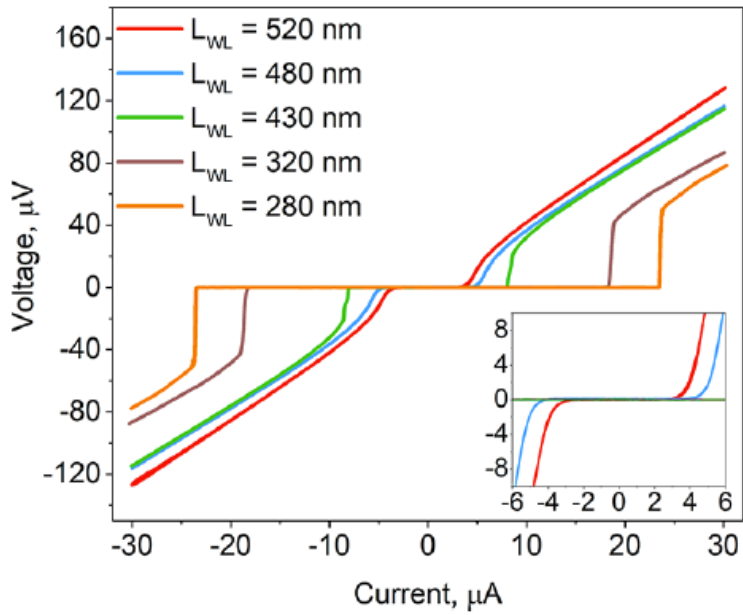
ACS Appl. Mater. Interfaces
 12 (2020) 970



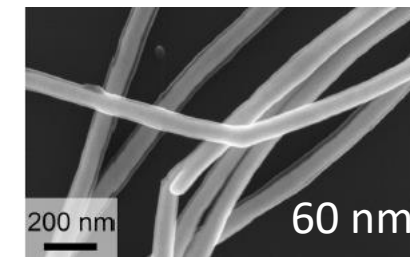
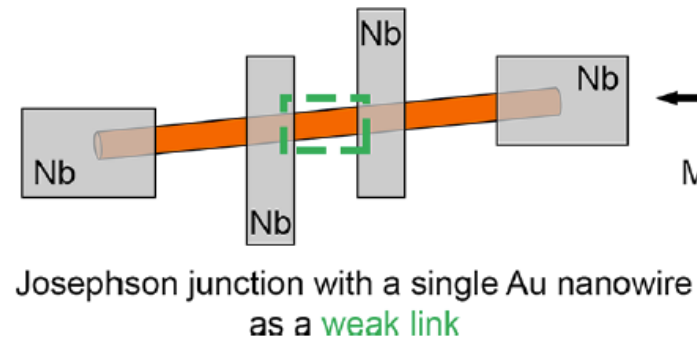
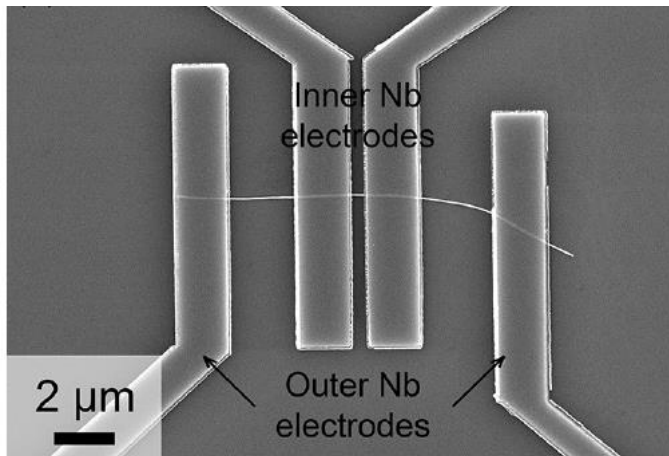
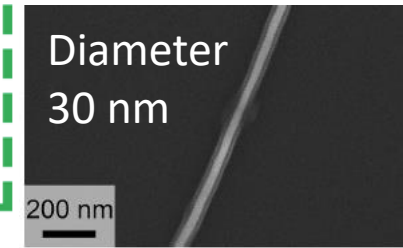
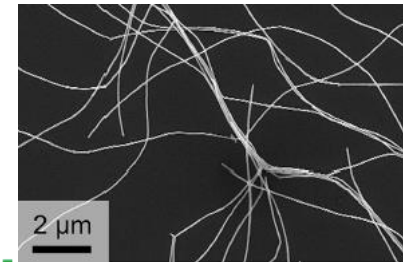
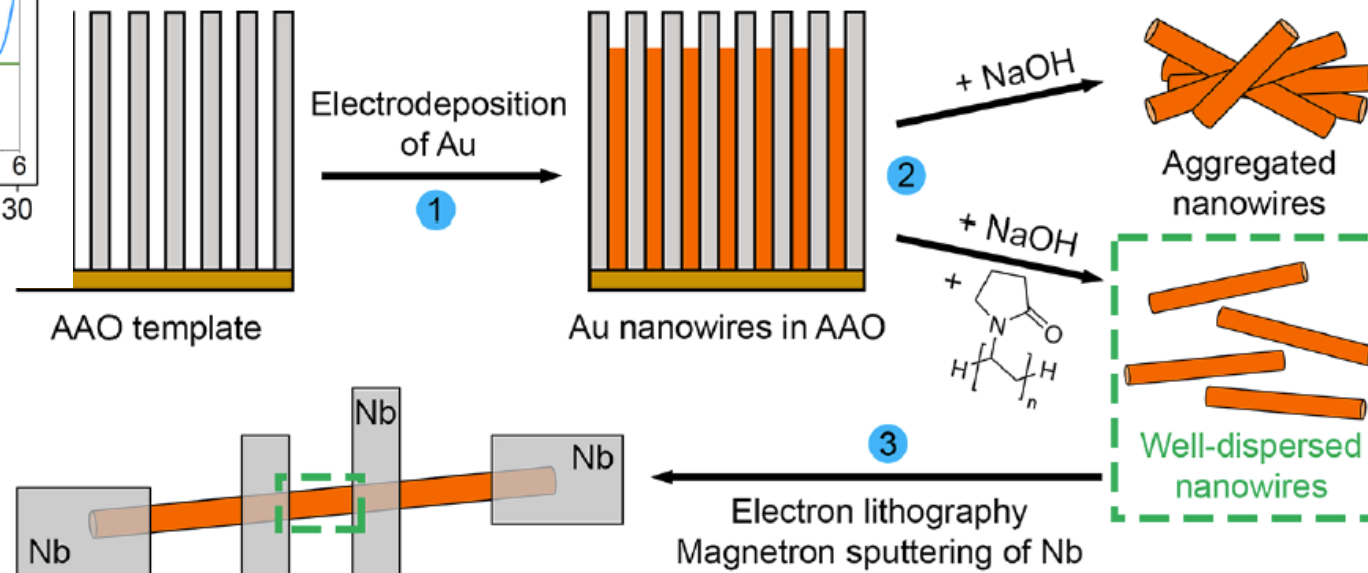
layers of graphene:
 0 (PBN), 1 (PBS),
 2 (PBD), 3 (PBT)



Single wire devices requiring contacts (example of Josephson junction)

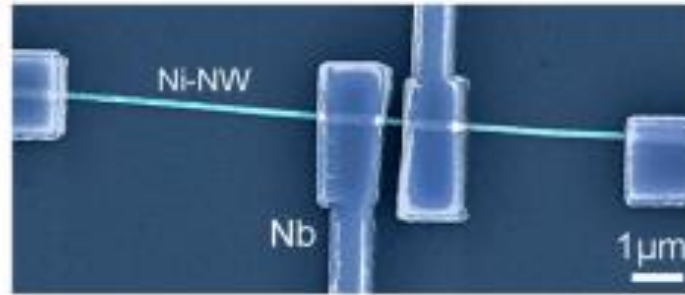
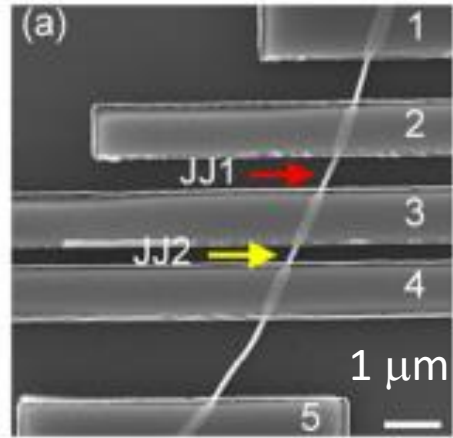


after AAO dissolution, surfactants are necessary to suppress wires aggregation; in this example, polyvinylpyrrolidone (PVP) is applied as surfactant



Single wire devices ... macroscopic contacts

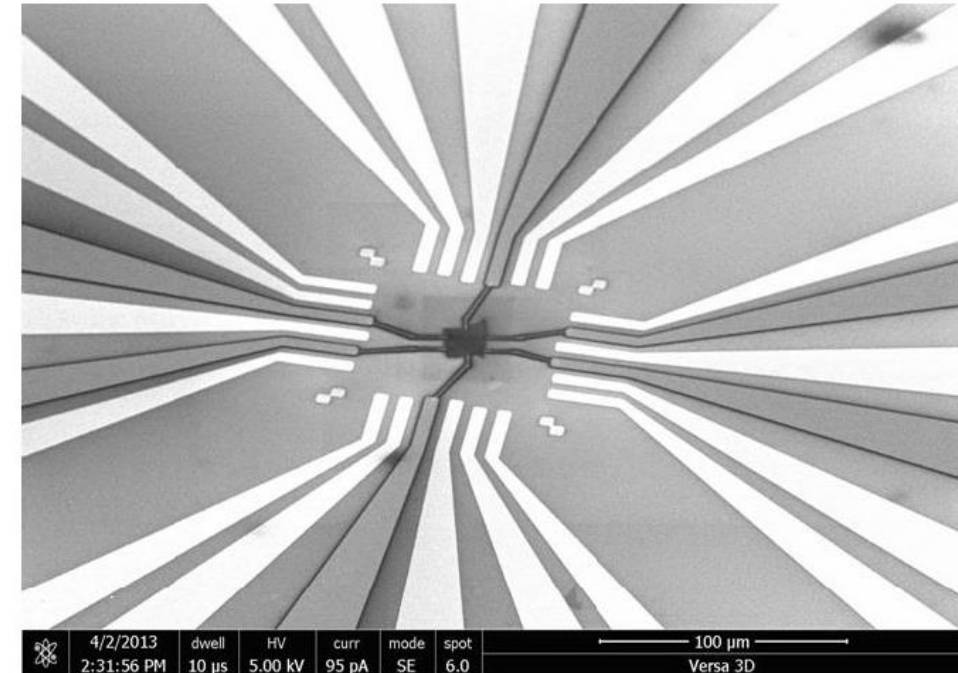
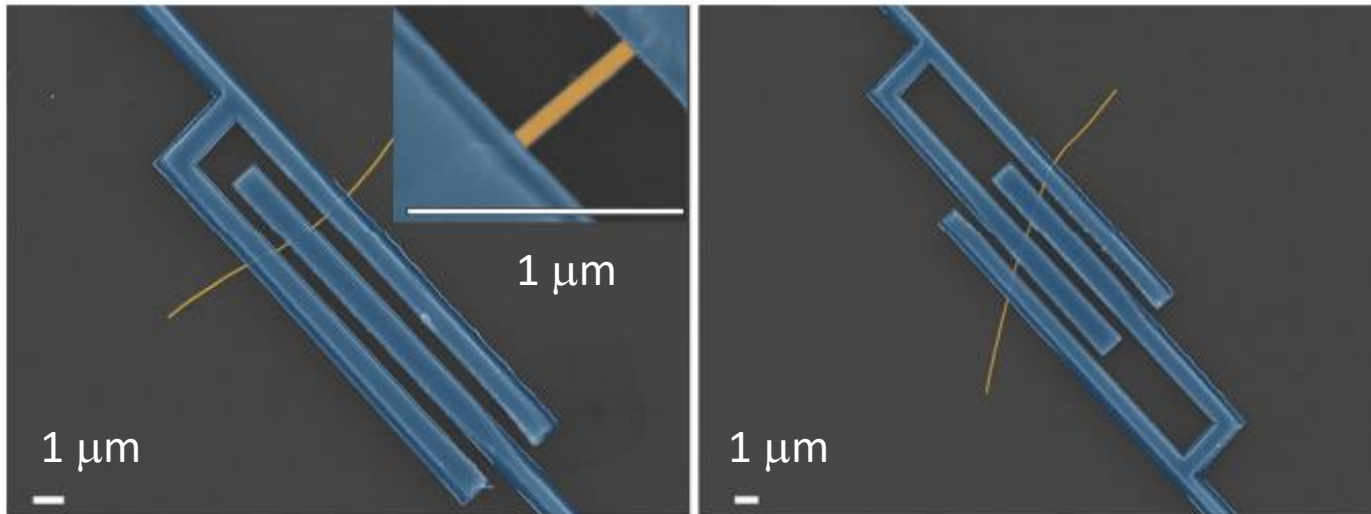
Sci. Rep. 9 (2019) 14470;
11 (2021) 17042



Macroscopic bonding (welding)

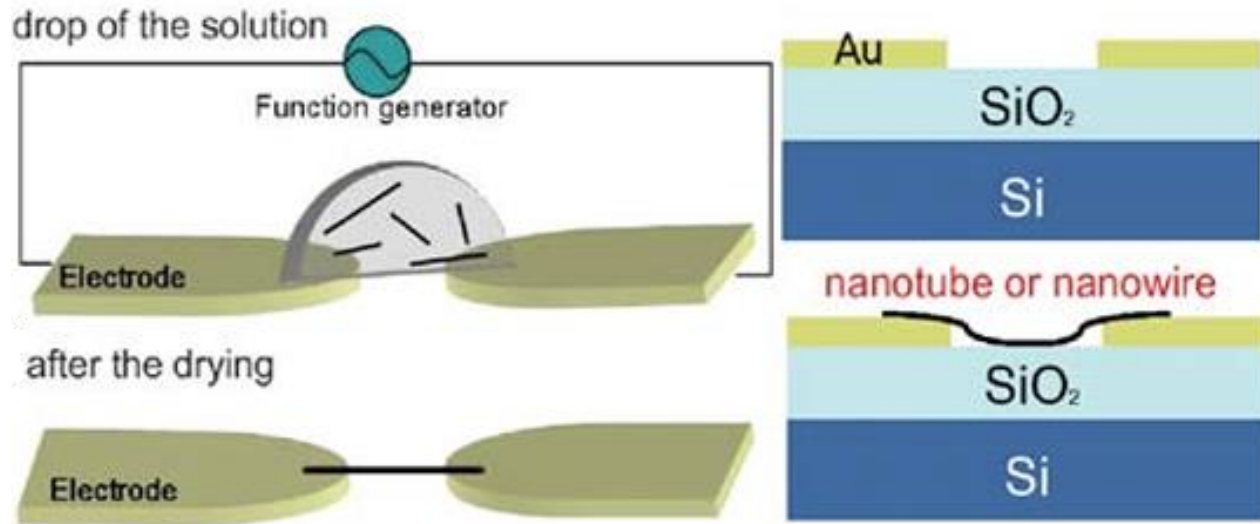


Macroscopic contact pads

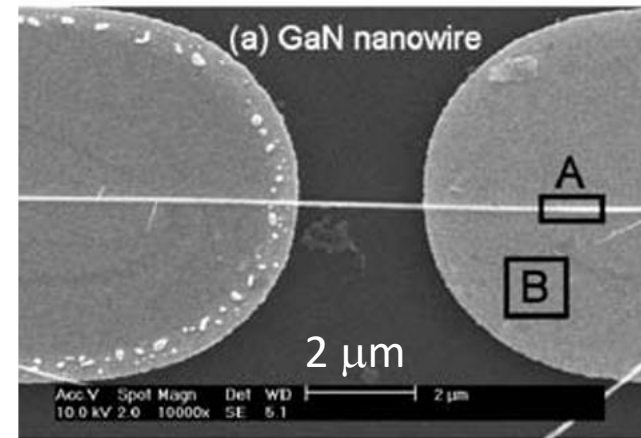


100 μm

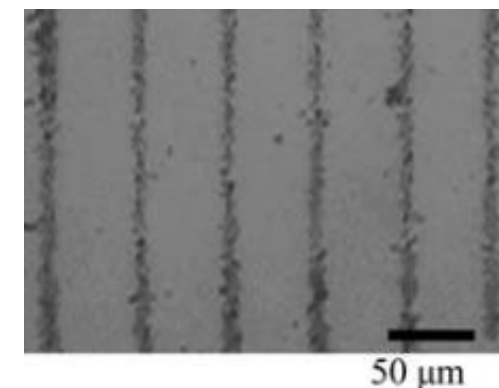
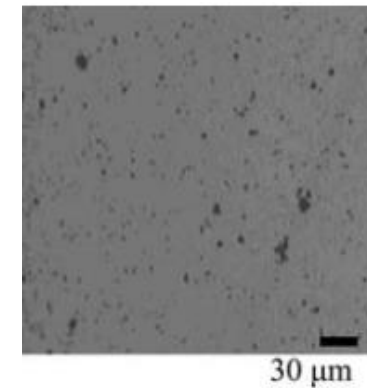
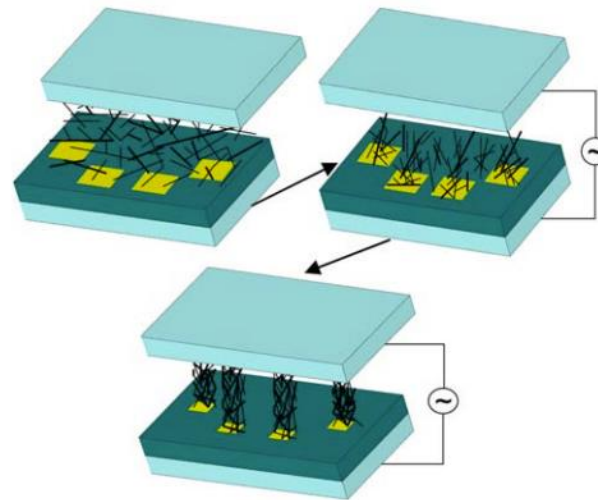
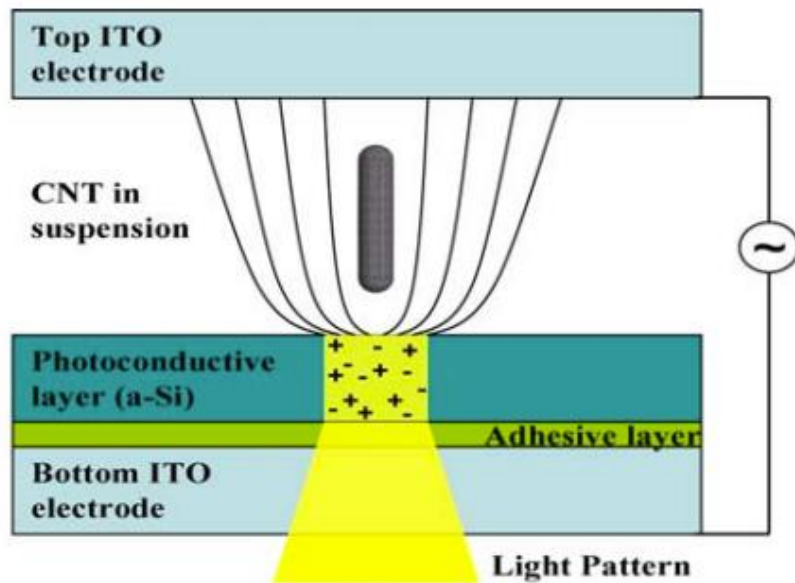
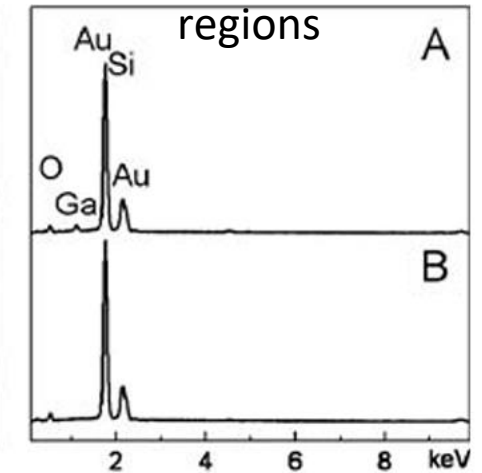
Electrophoresis as manipulation tool for 1D fragments



Curr. Appl. Phys. 6, Suppl. 1
(2006) e216-e219

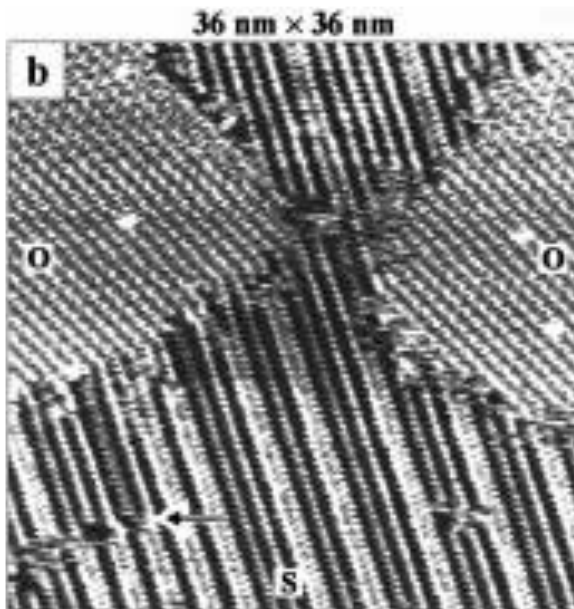


EDX analysis for A and B



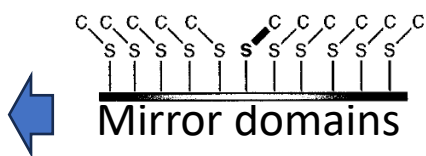
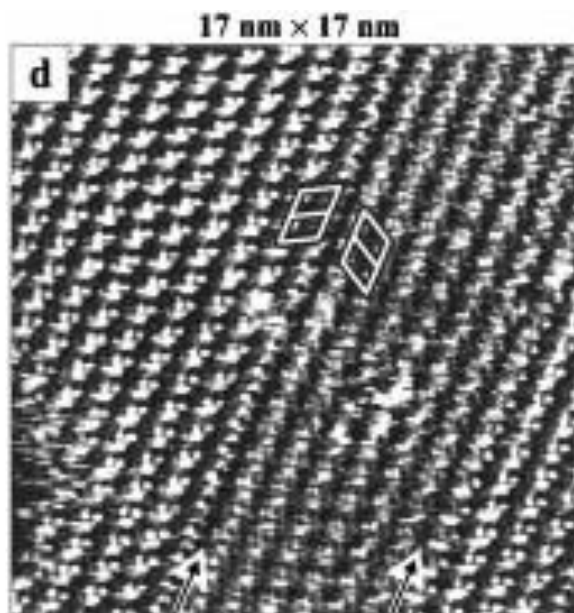
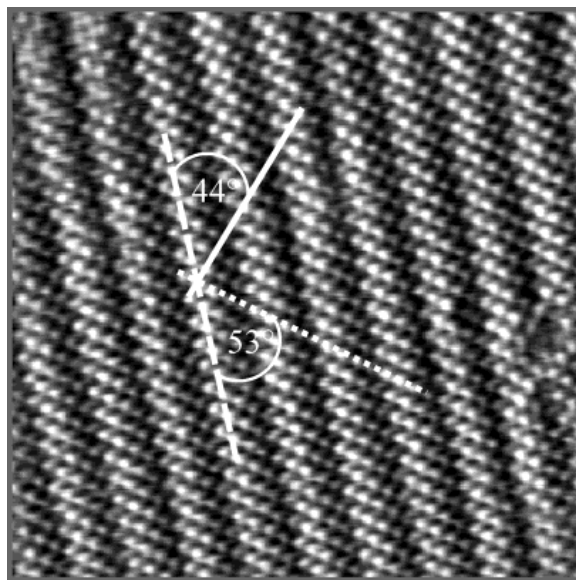
Microfluid Nanofluid 8 (2010) 609

Thiols (R-SH): molecular linkers for surfaces and 0D fragments (nanoparticles)

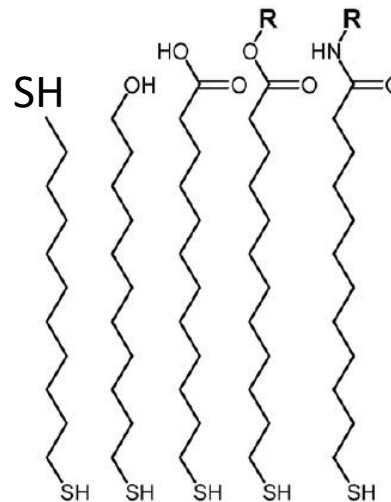


← Ethane thiol on Au(111)
Butane thiol on Au(100)

↓ 15x15 nm²



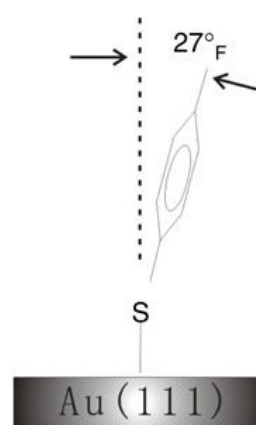
Langmuir 15 (1999) 2435;
19 (2003) 830



- SH groups and terminal functional groups of one and the same molecule can link to support surface and to nm-size particle respectively

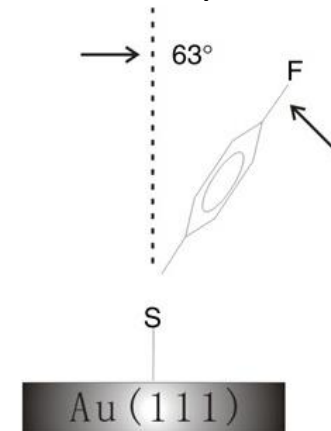
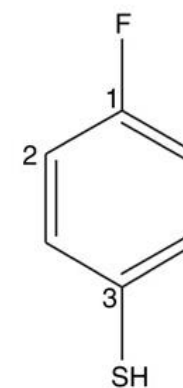
very usual linkers are dithiols

From solution:



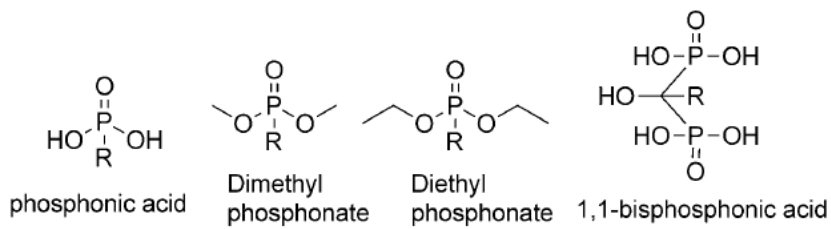
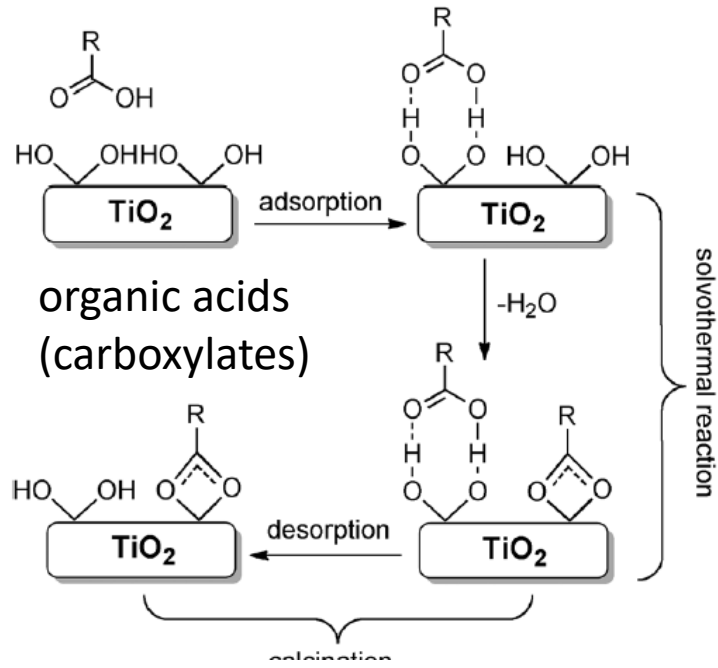
Surface coverage affects orientation
(tilt angle)

From vapor:

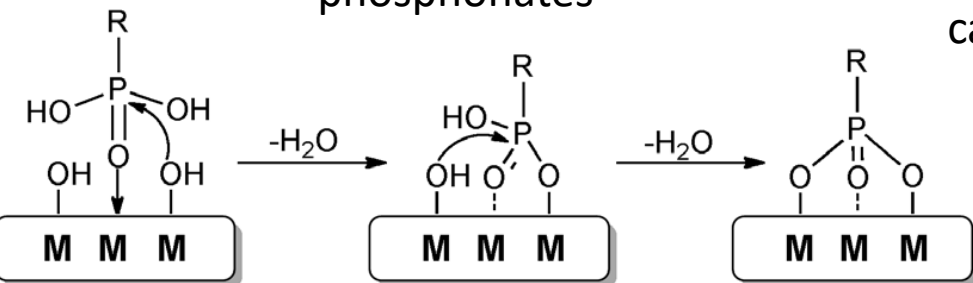


Surface Sci. Rep.63 (2008) 465

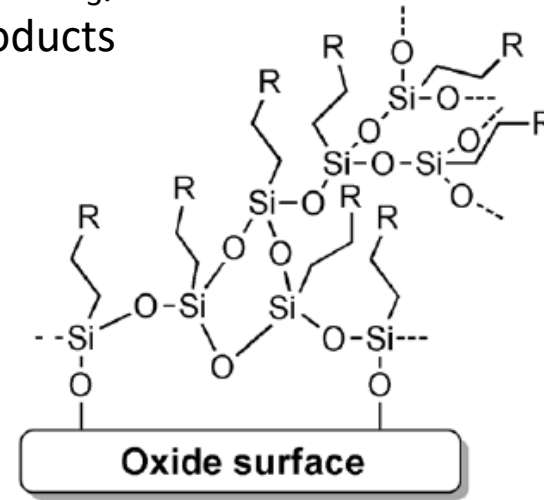
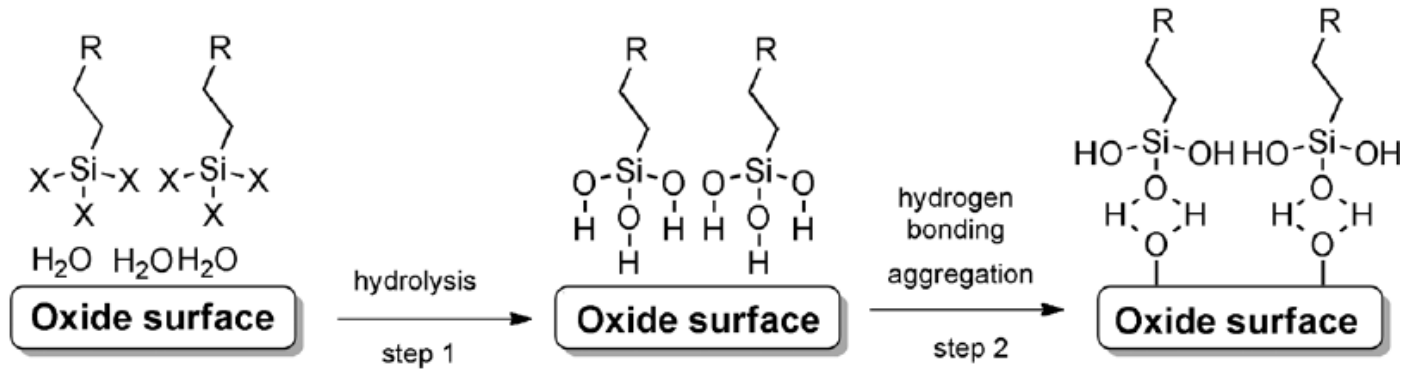
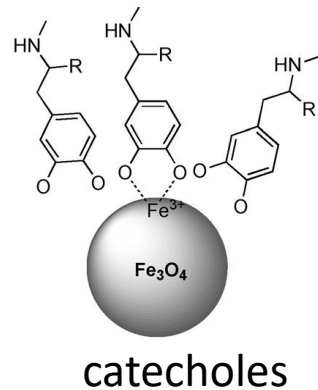
Molecular linkers for oxide surfaces (when thiols are less effective)



phosphonates



chlorosilane ($-\text{SiCl}_3$) hydrolysis products

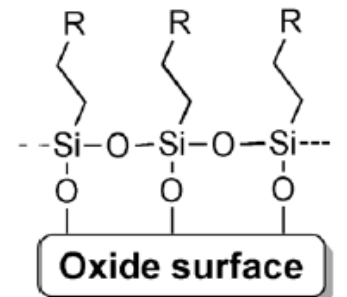


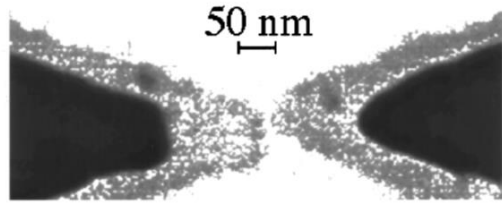
high water content
high concentration

step 3

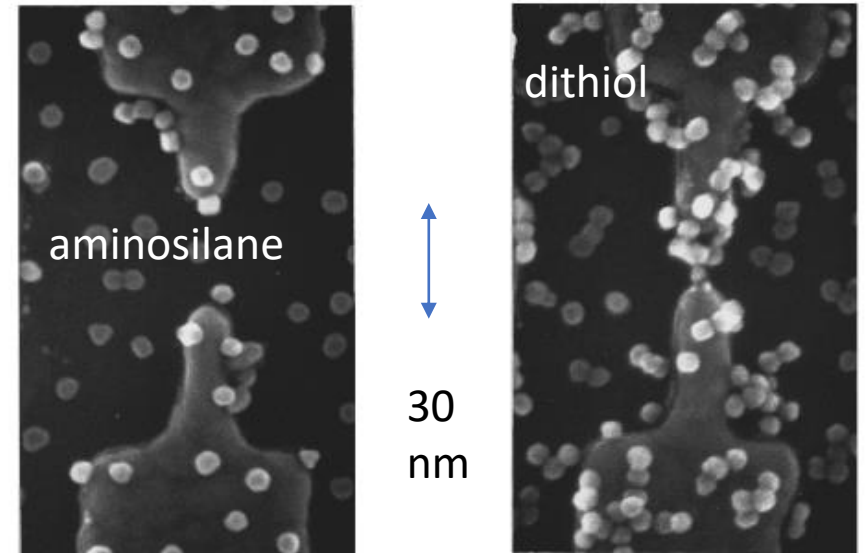
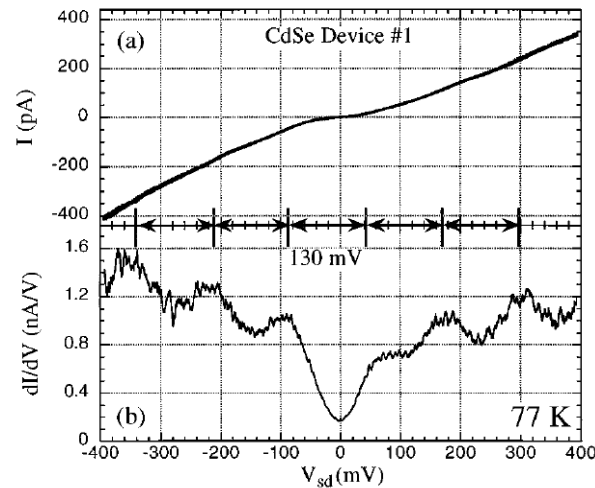
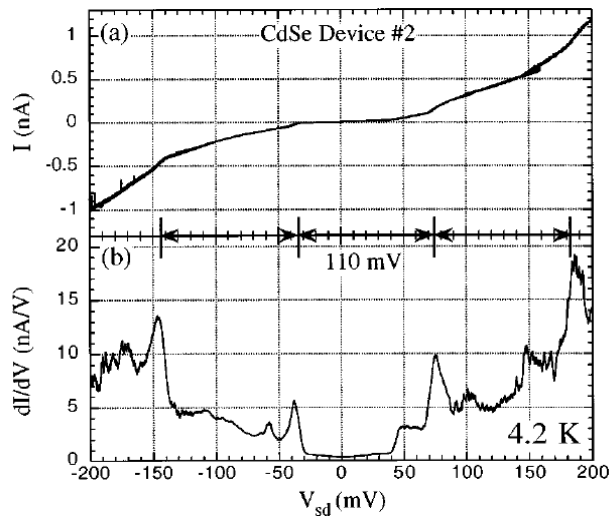
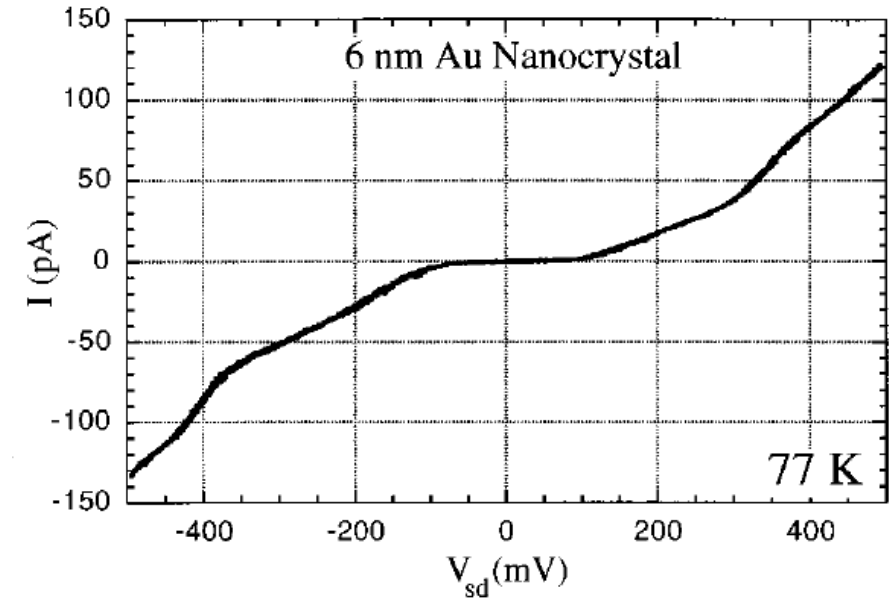
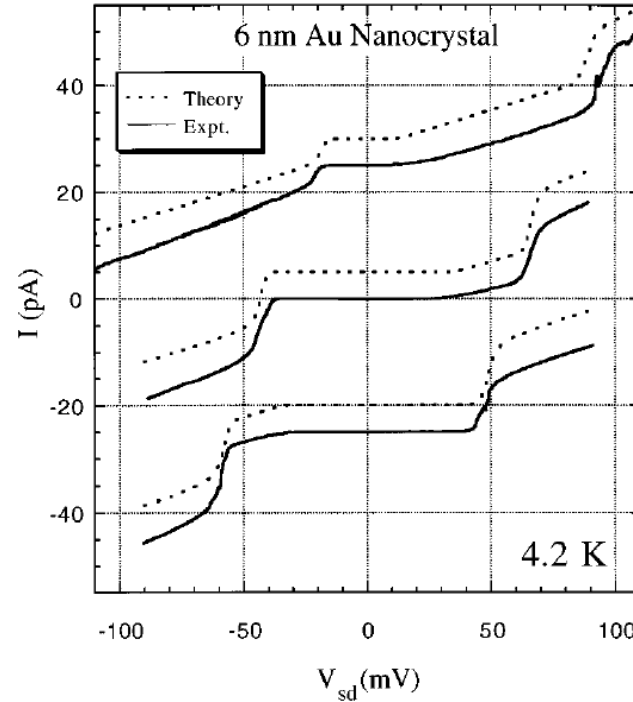
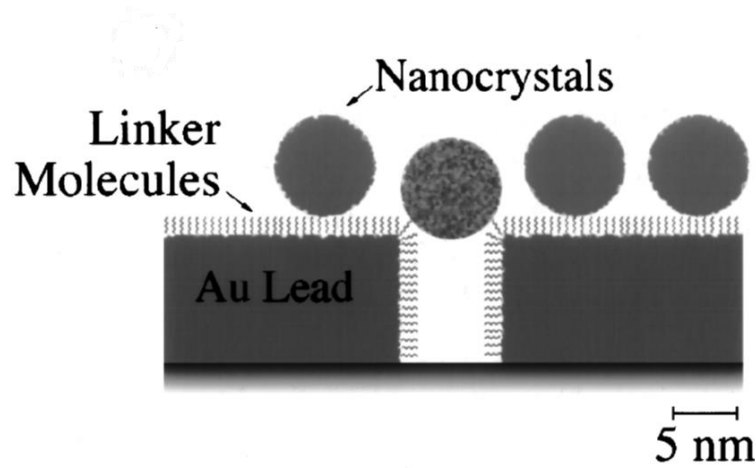
Condensation
 $-\text{H}_2\text{O}$

proper water content
ideal solvent
ideal concentration

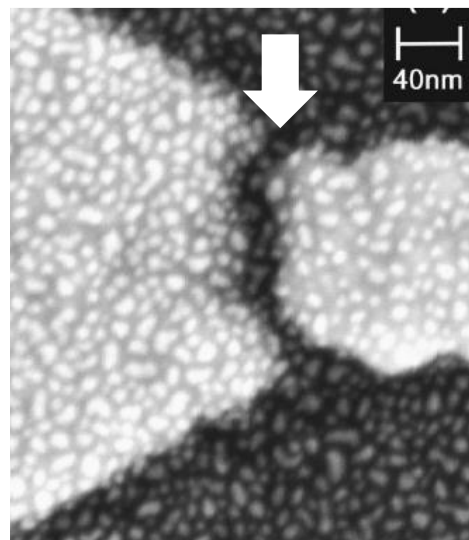
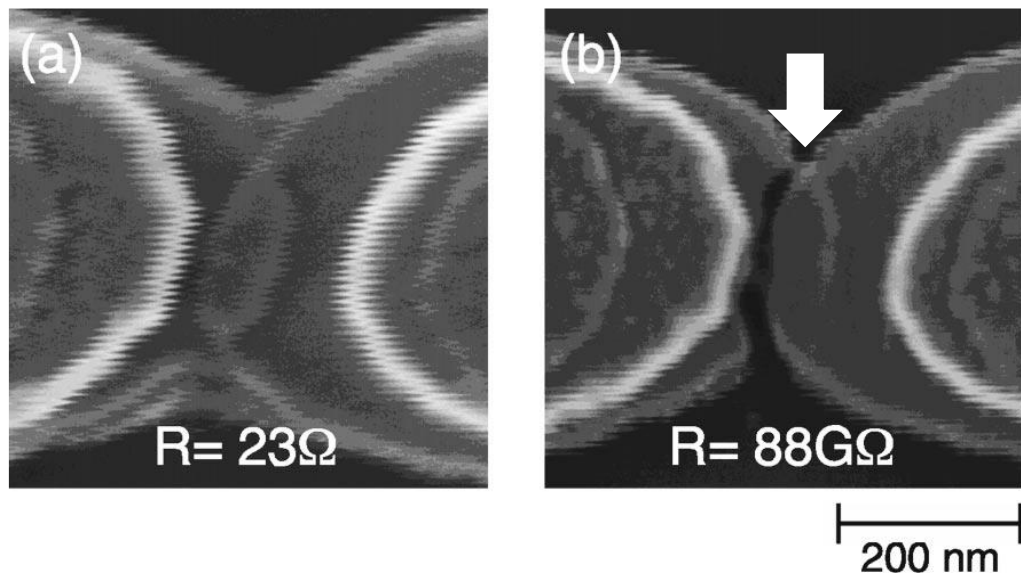




gap is created by shadow evaporation

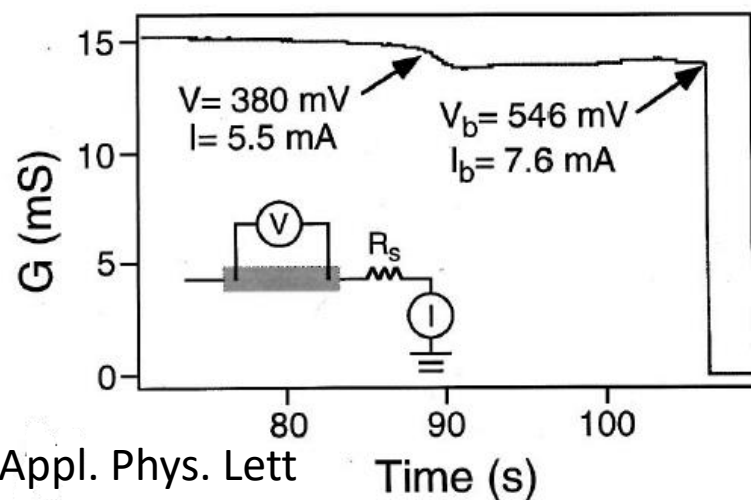
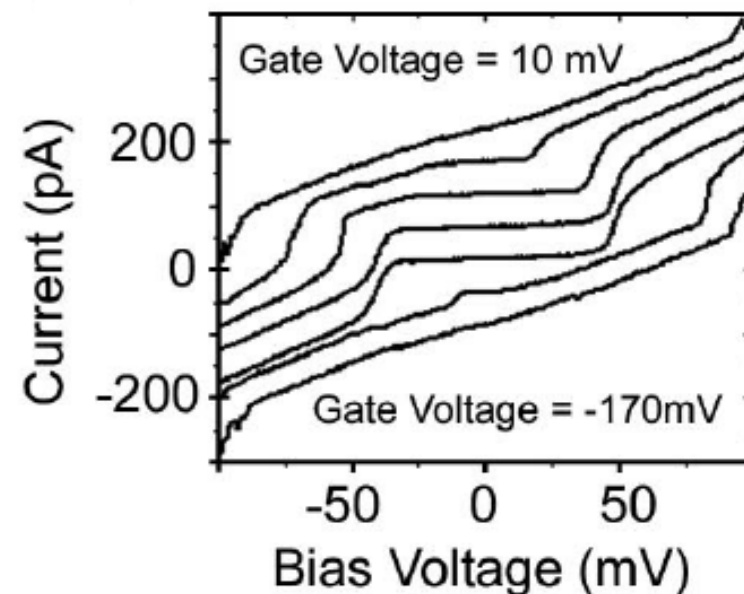


nm-size gaps: fabricated by electromigration, for single electron transistors

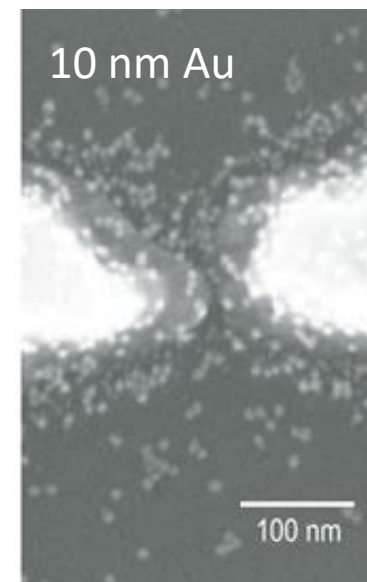
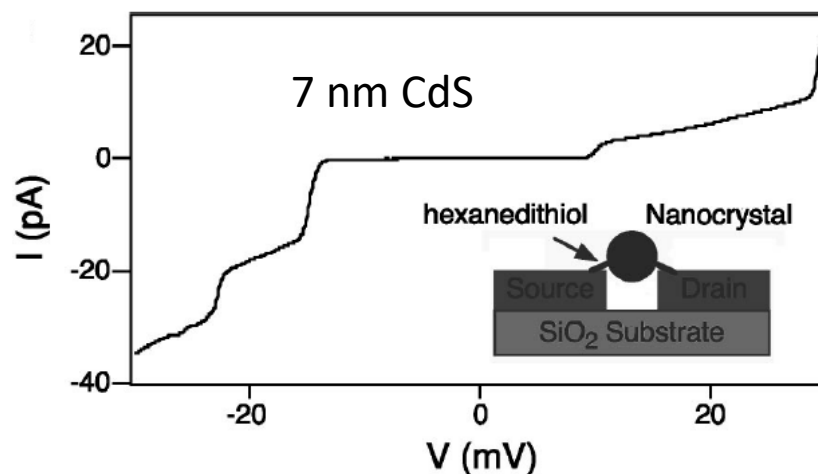


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Evaporated Au islands, 5 - 15 nm



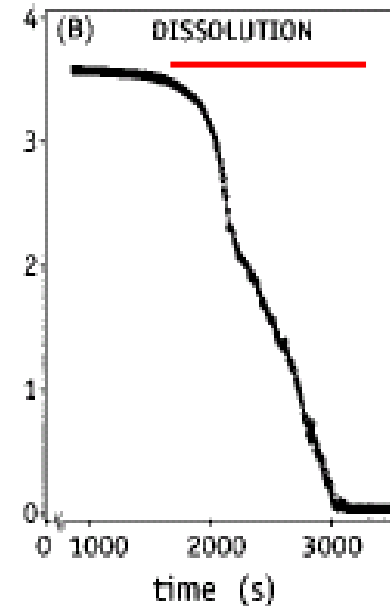
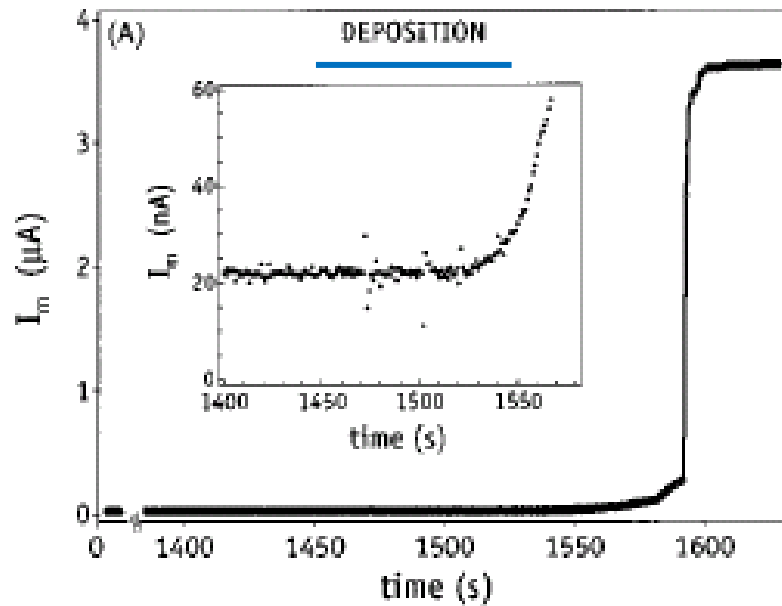
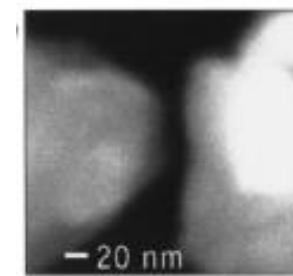
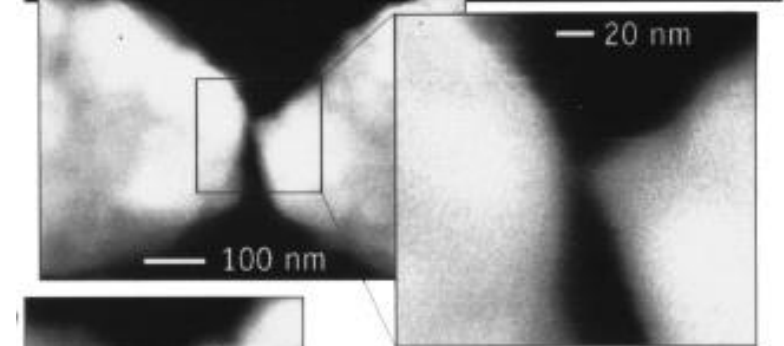
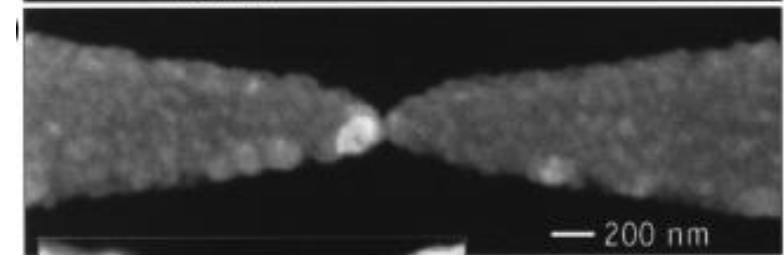
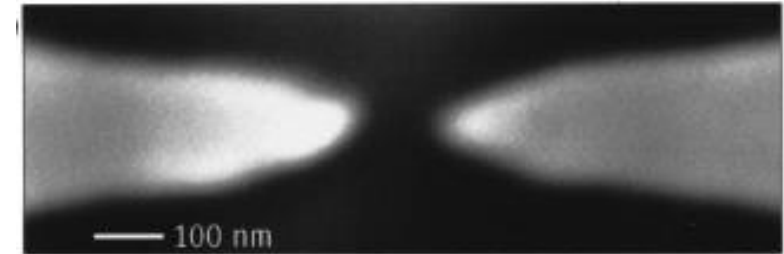
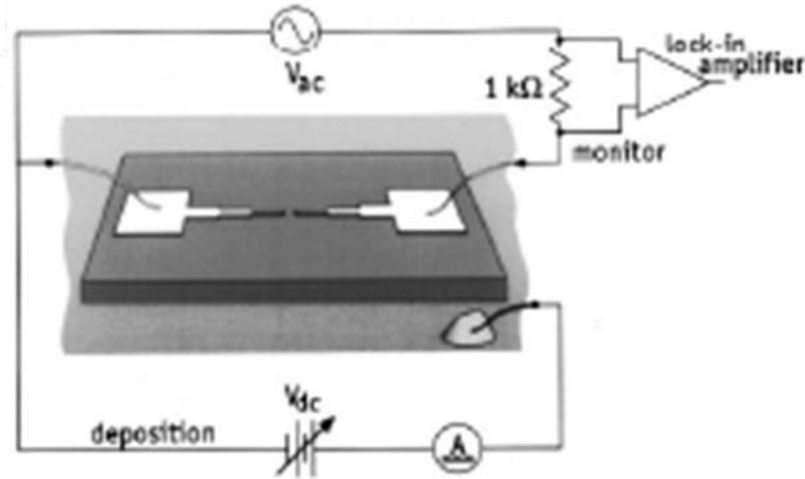
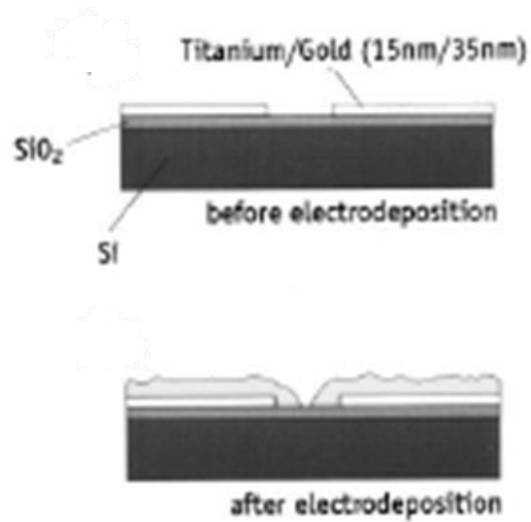
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75 (1999) 301



5 nm gap,
aminosilane
linker

AIP Conf. Proc.
850 (2006) 1438

Gaps formed by electrodeposition and dissolution $[\text{Au}(\text{CN})_4]^- + 3 e \rightleftharpoons \text{Au} + 4\text{CN}^-$



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Assembling: reviews

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